

Offline analysis for CEPC vertex detector test beam at DESY

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11/01/2023

Introduction

► Motivation

- Building a standalone offline analysis framework for CEPC vertex detector TaiChu pixel chip test beam
- Track reconstruction

no magnetic

straight line fit

no considering multi-scattering currently

- Track alignment

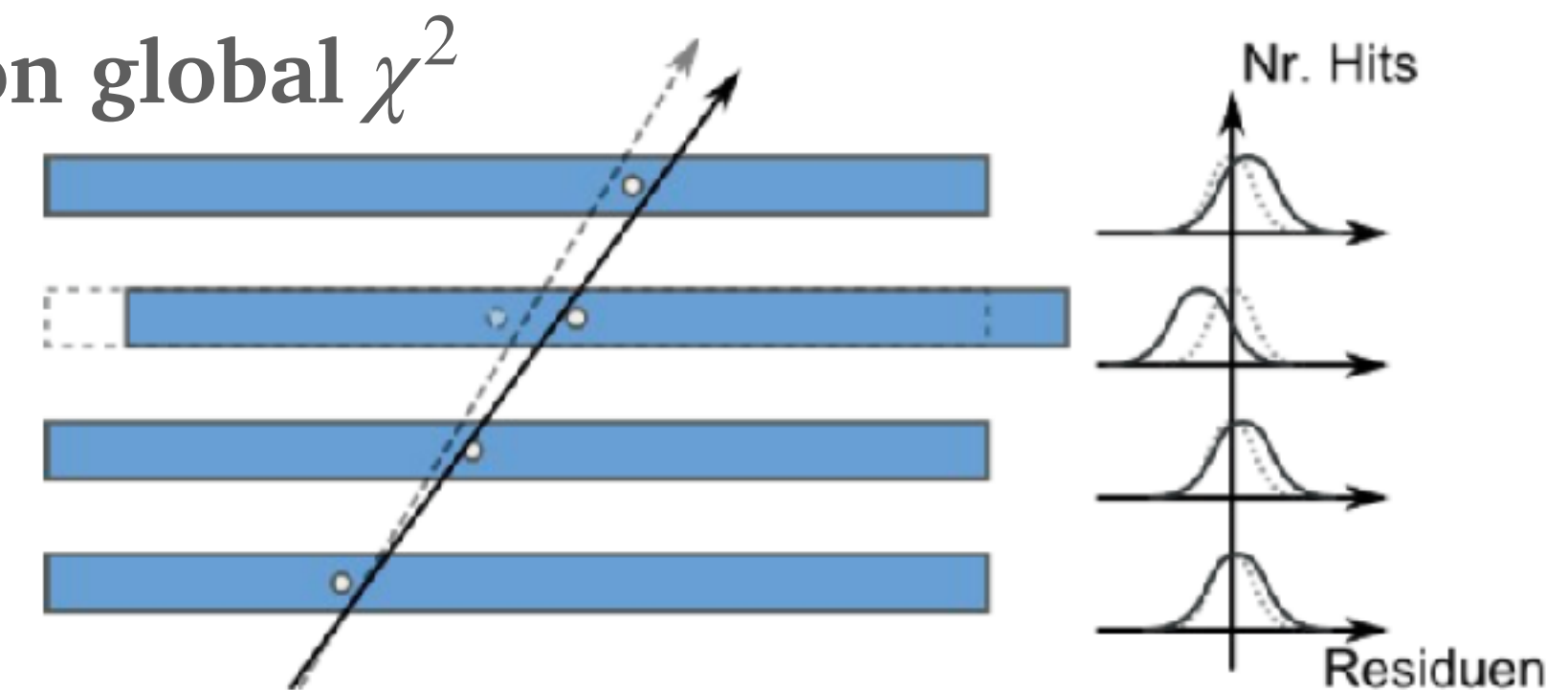
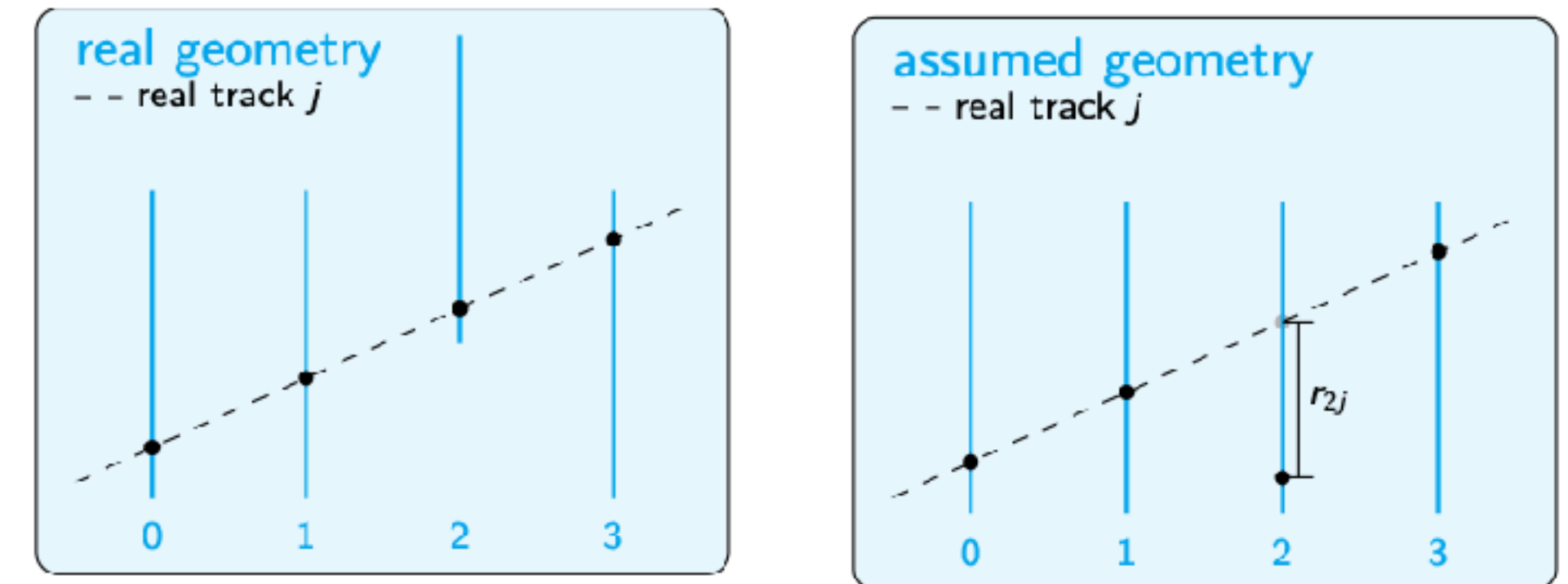
correction for the misalign chip position

misalignment effects the resolution of detector

find the solution of real geometry for global tracks based on global χ^2

► TaiChu silicon pixel detector

- Pixel size: 25 μm
- Theoretical resolution: $25\mu\text{m}/\sqrt{12} \sim 7.22 \mu\text{m}$
- The experimental resolution should be better than theoretical resolution due to charge sharing



Residual: distance of measured hit with the intersection point of track in the measured chip

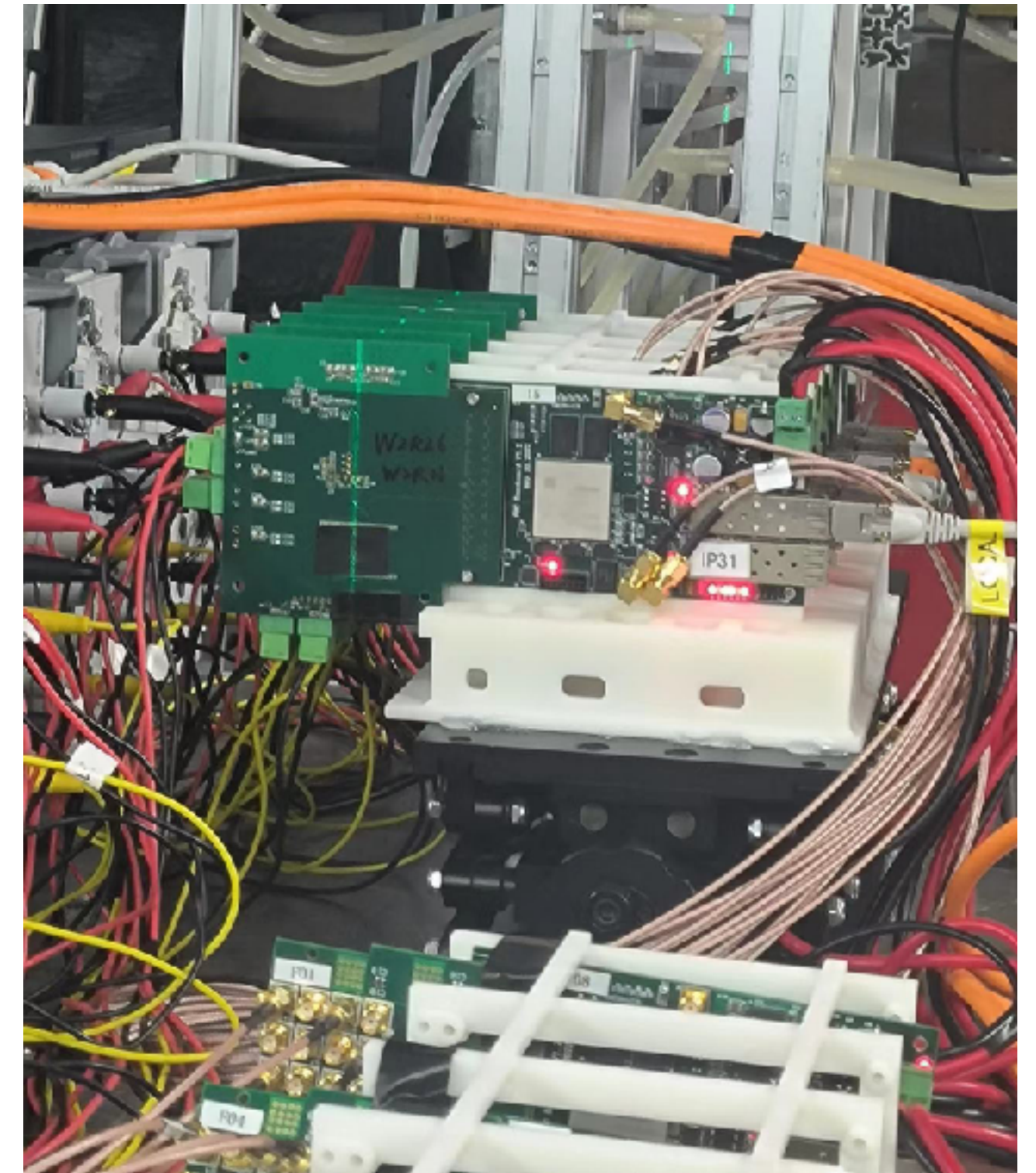
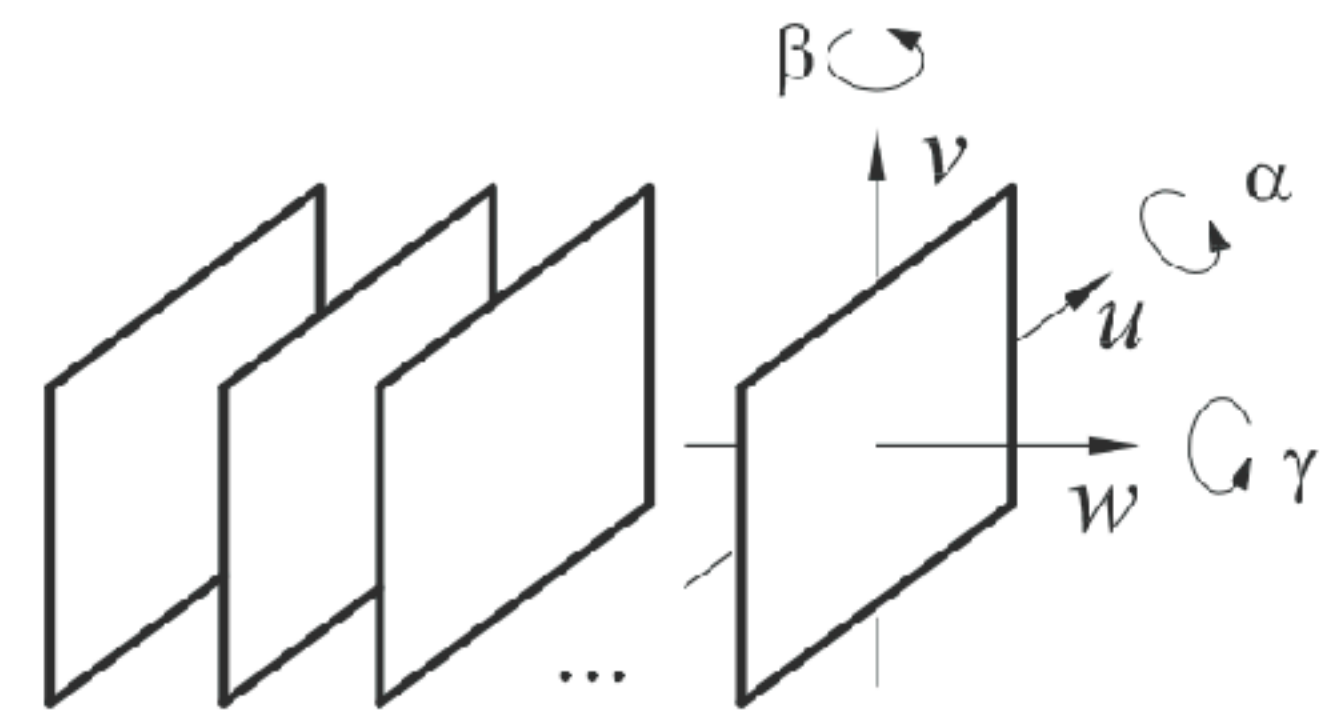
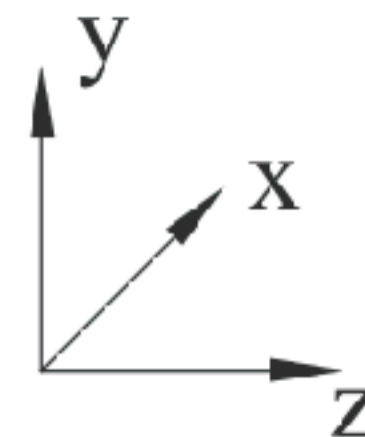
Track reconstruction

- ▶ Setup
 - 6 layer chips
 - 4cm between each other
 - electron beam energy 3-6 GeV
 - One of the chips is the detector under test (dut), the others are the telescope
- ▶ Steps for track finding and reconstruction
 - Finding hits in every chip with same time stamp of FPGA (+/- 1)
 - Forming adjacent hits into a cluster
 - No considering multiple clusters on one chip for one track currently
- ▶ Track fitting
 - least squares line fitting

$$x = a_1 z + b_1;$$

$$y = a_2 z + b_2;$$

$$\text{Chi2 definition: } \chi^2(\alpha) = \sum_{i=1}^n \frac{(f(x_i, \alpha) - e_i)^2}{\sigma_i^2}, \text{ sigmax} = \text{sigmay} = 25\mu\text{m}/\sqrt{12}$$



Track alignment

- ▶ Method - millepede matrix method

p: alignment parameters, q: track parameters

- minimize: $\chi^2 = \sum_{i \in \text{tracks}} \vec{r}_i^T V_i^{-1} \vec{r}_i$, is residual $\vec{r}_i(\vec{p}, \vec{q}_i)$, V is the covariance matrix

$$\frac{d\chi^2(\vec{p})}{d\vec{p}} = 0 \longrightarrow \chi^2(\vec{p}) = \chi^2(\vec{p}_0) + \left. \frac{d\chi^2(\vec{p})}{d\vec{p}} \right|_{\vec{p}=\vec{p}_0} (\vec{p} - \vec{p}_0) \longrightarrow \underbrace{(J^T V_i^{-1} J)}_C \Delta \vec{p} = \underbrace{J^T V_i^{-1} \vec{r}_i(\vec{p}_0)}_b$$

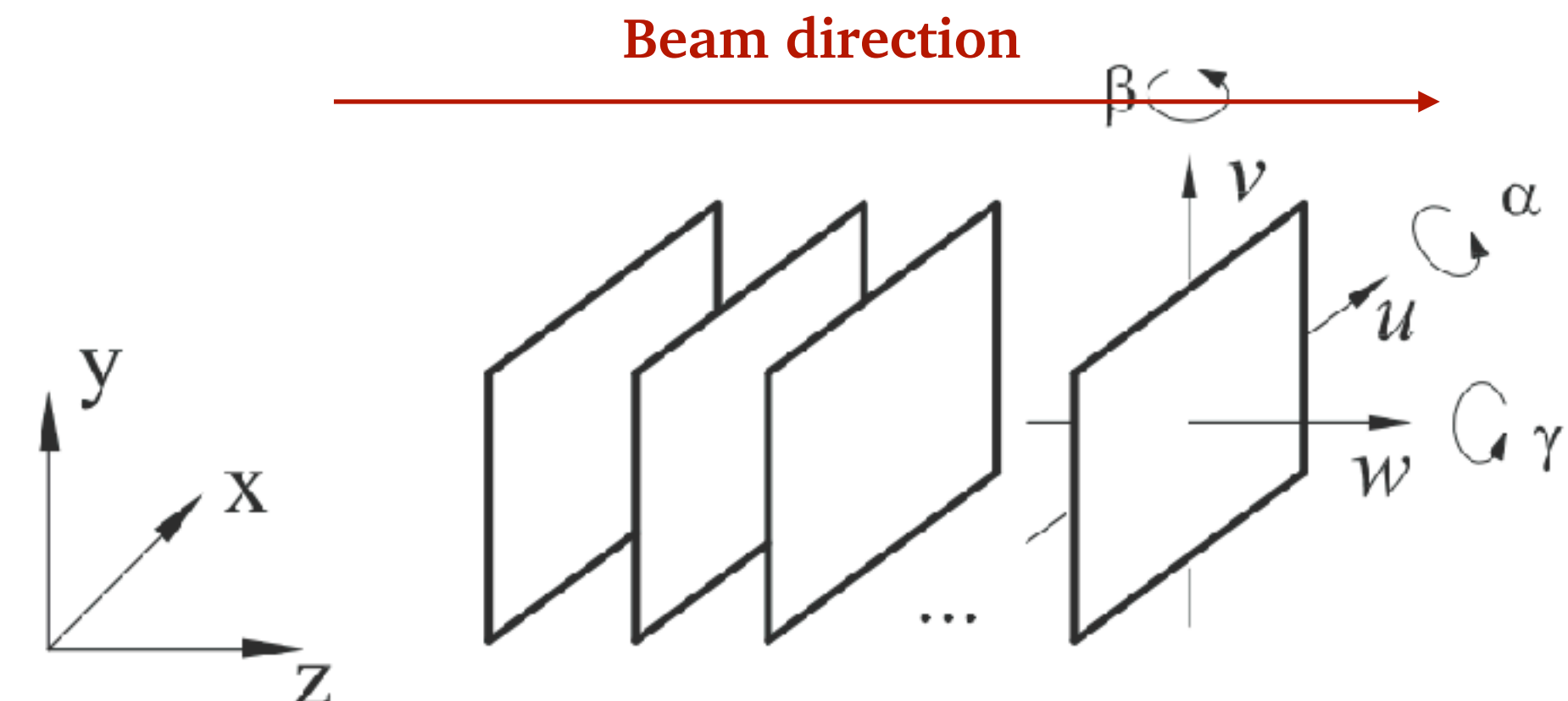
$$C \Delta \vec{p} = \vec{b}$$

- invert the Matrix C to find alignment correction Δp
- reduce matrix C for alignment only

$$S = C_{11} - C_{12} C_{22}^{-1} C_{21}$$

$$\begin{pmatrix} C_{11} & C_{12} \\ C_{21} & C_{22} \end{pmatrix} \begin{pmatrix} \Delta \vec{p}_1 \\ \Delta \vec{p}_2 \end{pmatrix} = \begin{pmatrix} \vec{b}_1 \\ \vec{b}_2 \end{pmatrix} \longrightarrow \begin{pmatrix} \Delta \vec{p}_1 \\ \Delta \vec{p}_2 \end{pmatrix} = \begin{pmatrix} S^{-1} & -S^{-1} C_{21}^T C_{22}^{-1} \\ -C_{22}^{-1} C_{21} S^{-1} & C_{22}^{-1} - C_{22}^{-1} C_{21} S^{-1} C_{21}^T C_{22}^{-1} \end{pmatrix} \begin{pmatrix} \vec{b}_1 \\ \vec{b}_2 \end{pmatrix} \longrightarrow \Delta \vec{p}_1 = S^{-1} (\vec{b}_1 - C_{21}^T C_{22}^{-1} \vec{b}_2)$$

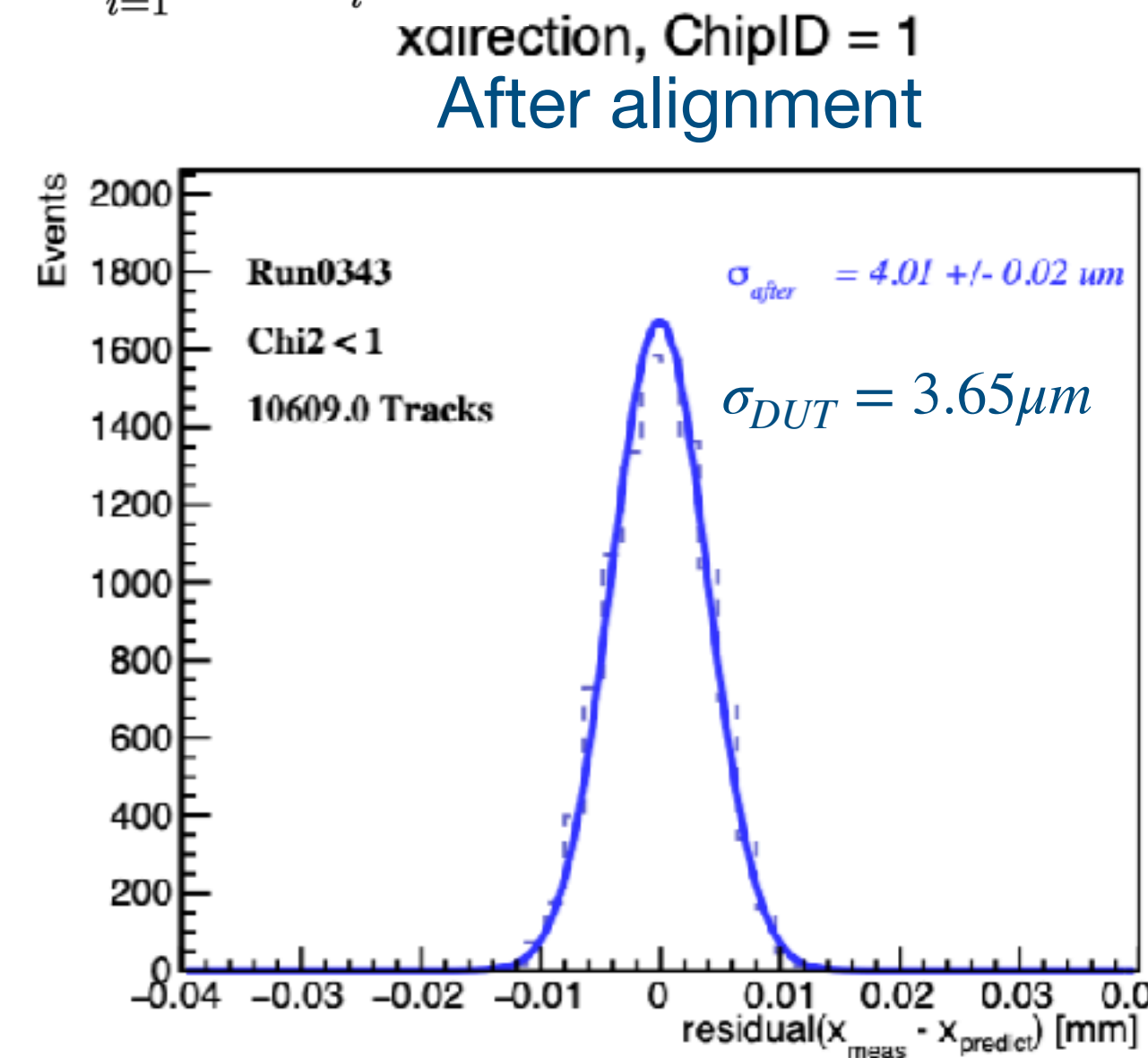
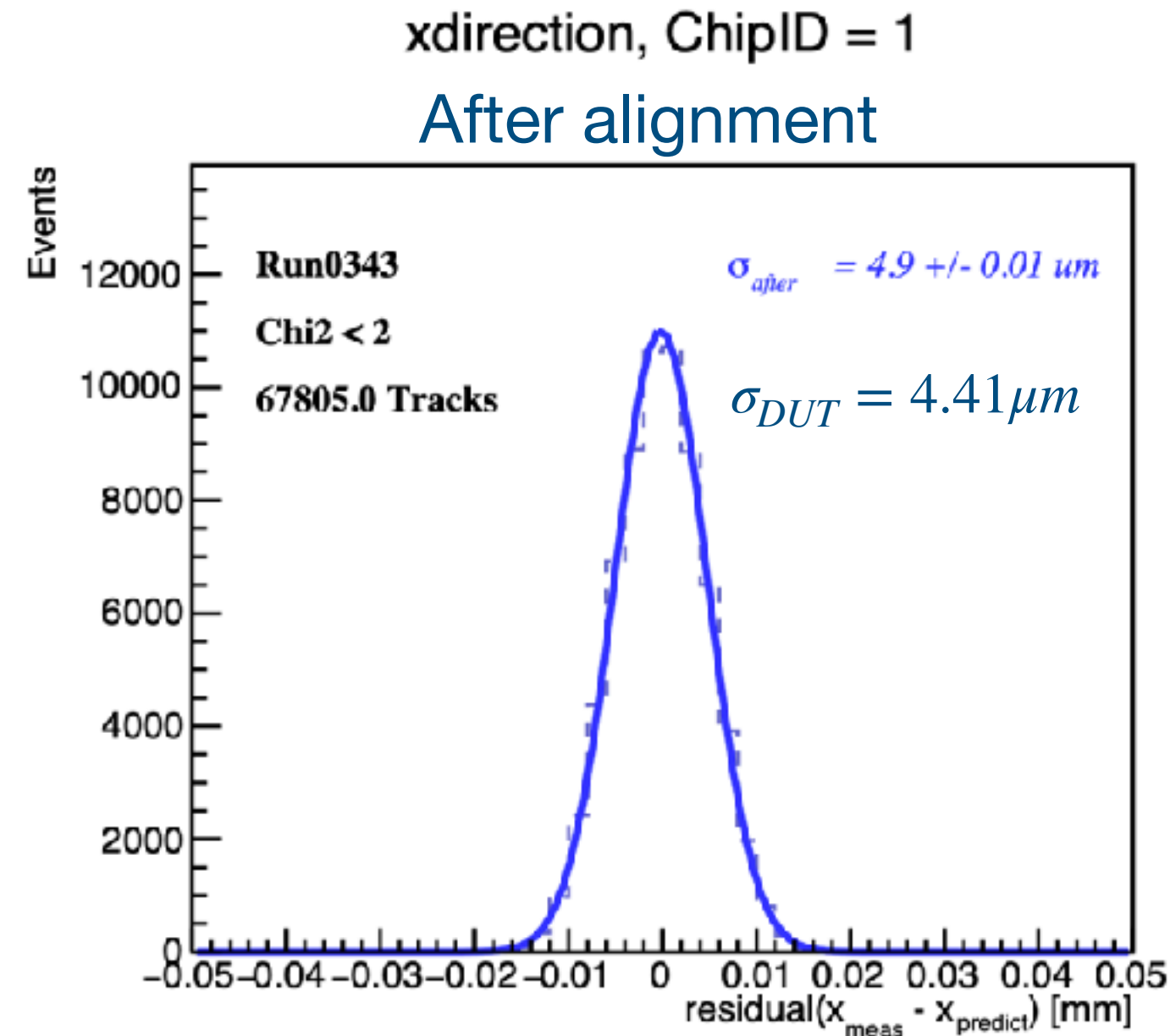
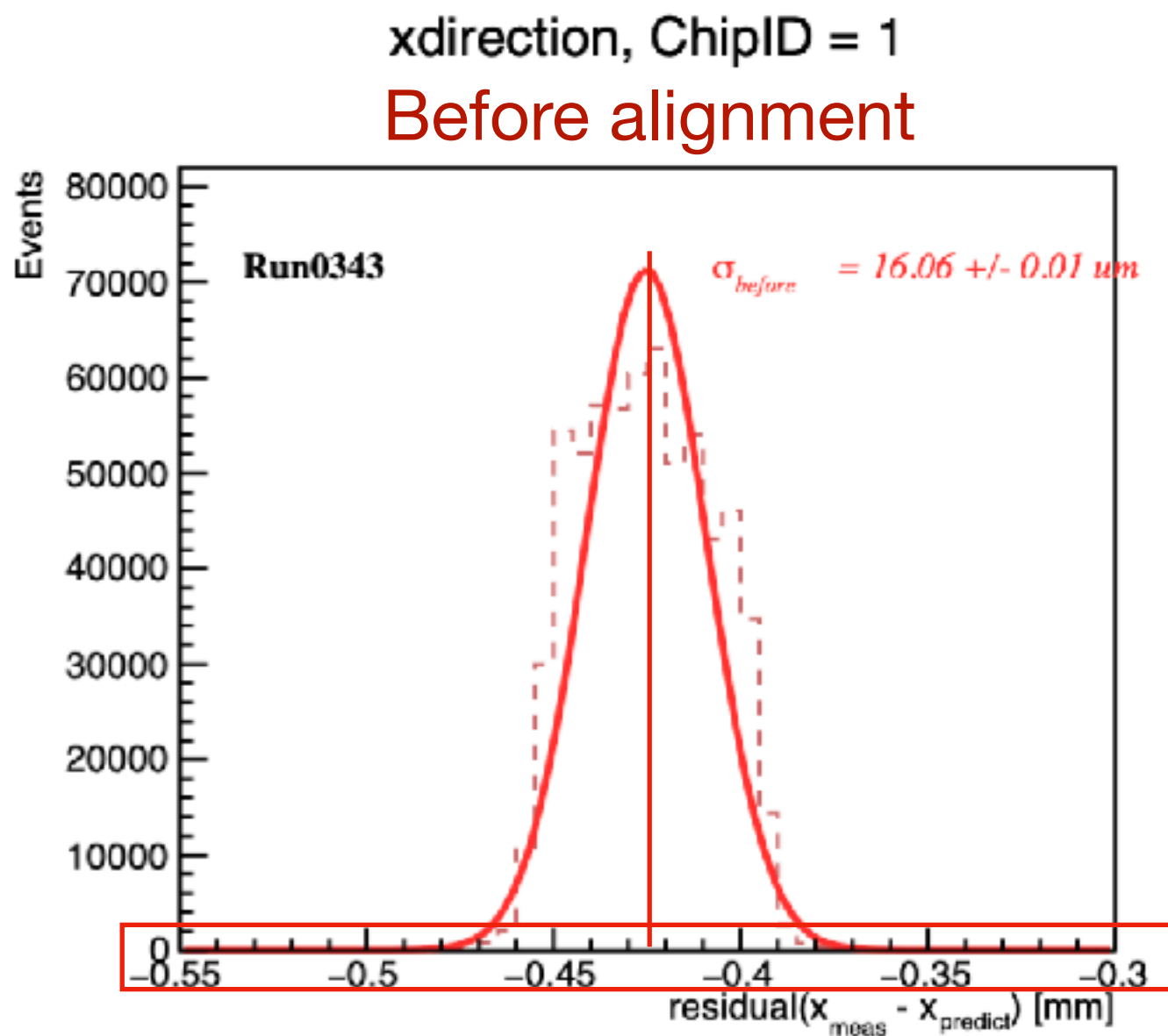
- Matrix S with smaller size than C, and C_{22} is easy to invert
- ▶ Six alignment parameters considered
 - Translation along X, Y, Z direction
 - Rotation around X, Y, Z axis



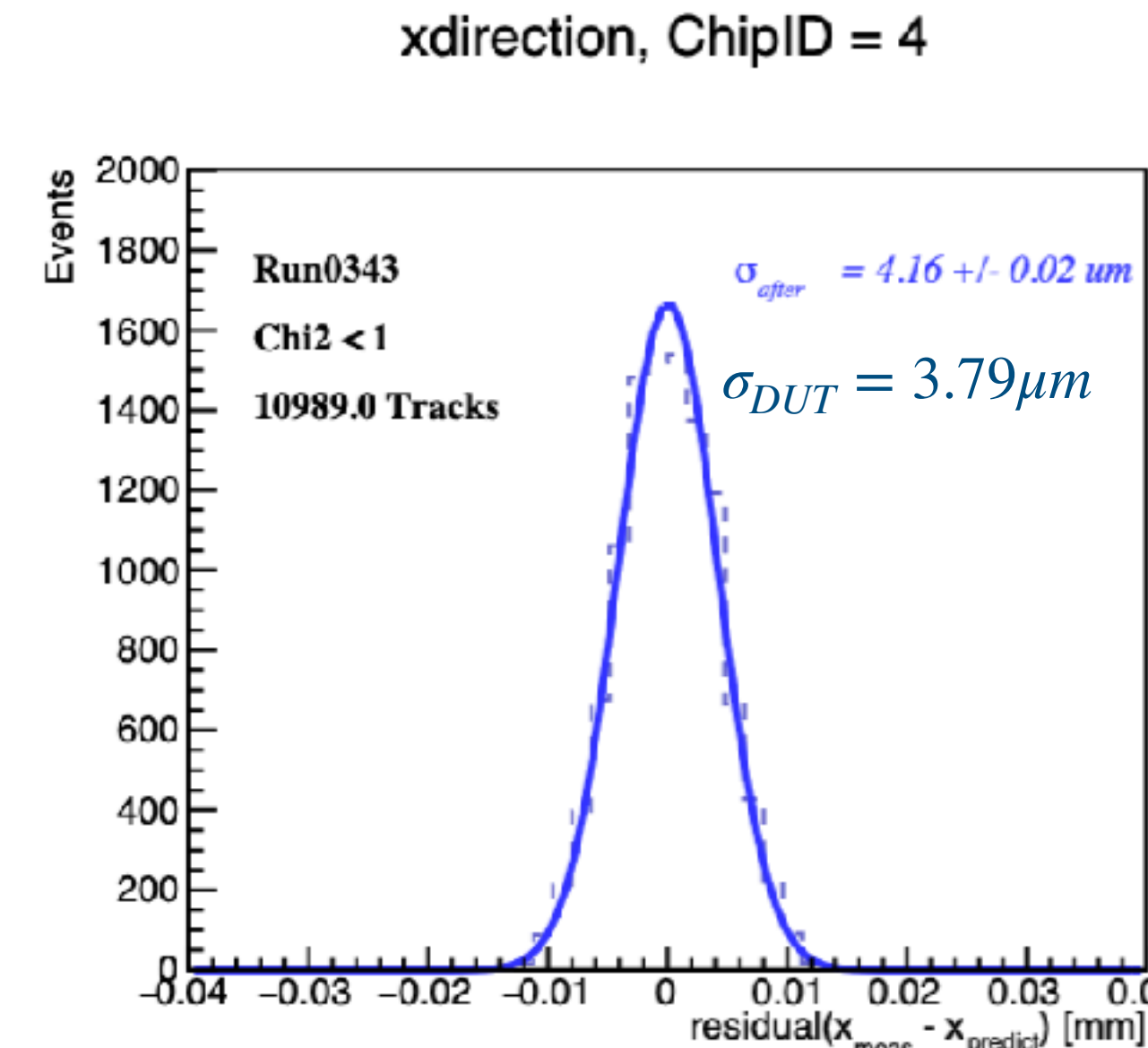
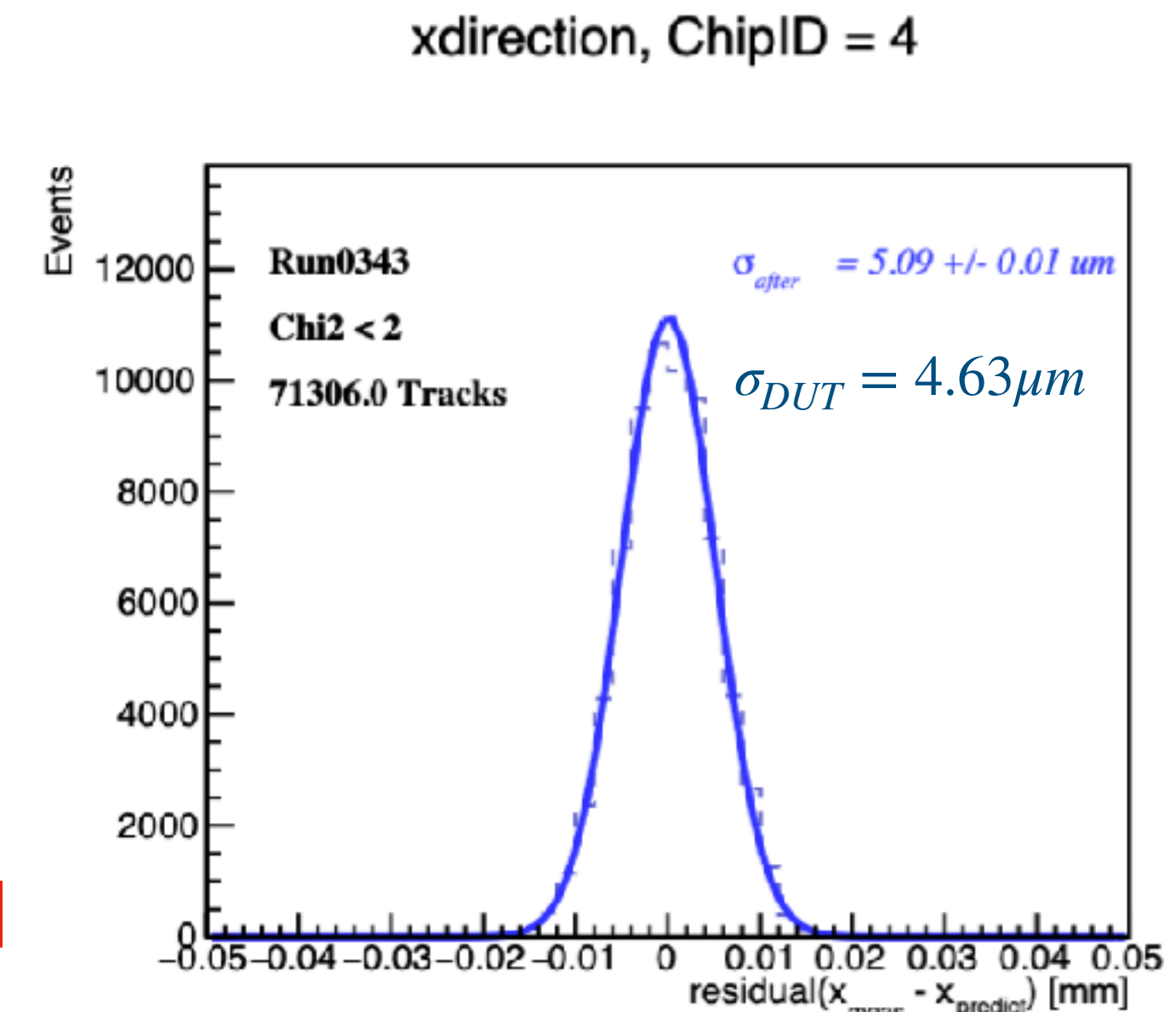
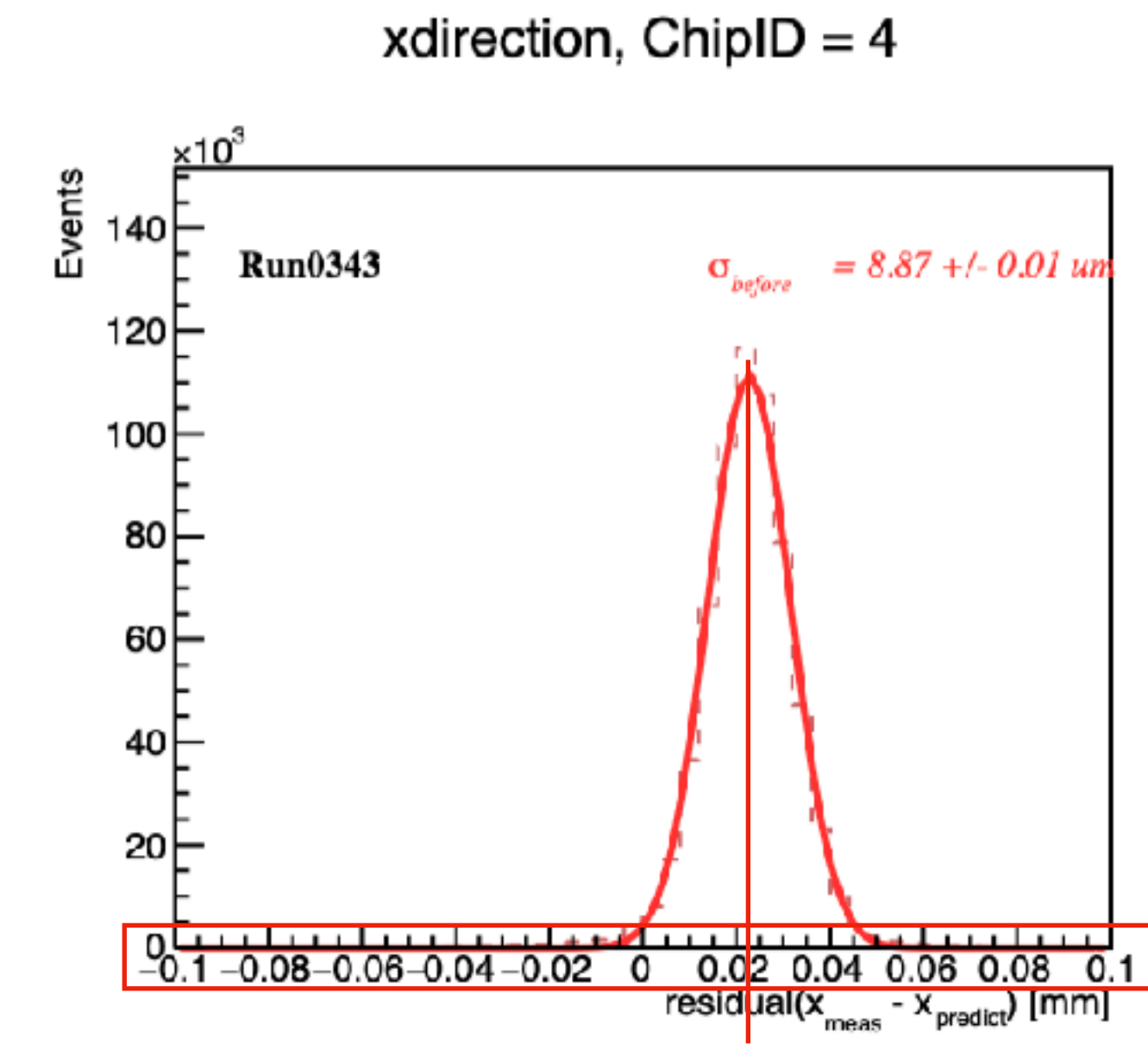
► Residual plots before and after alignment (4GeV)

Residual: distance of measured hit with the intersection point of track in the measured chip

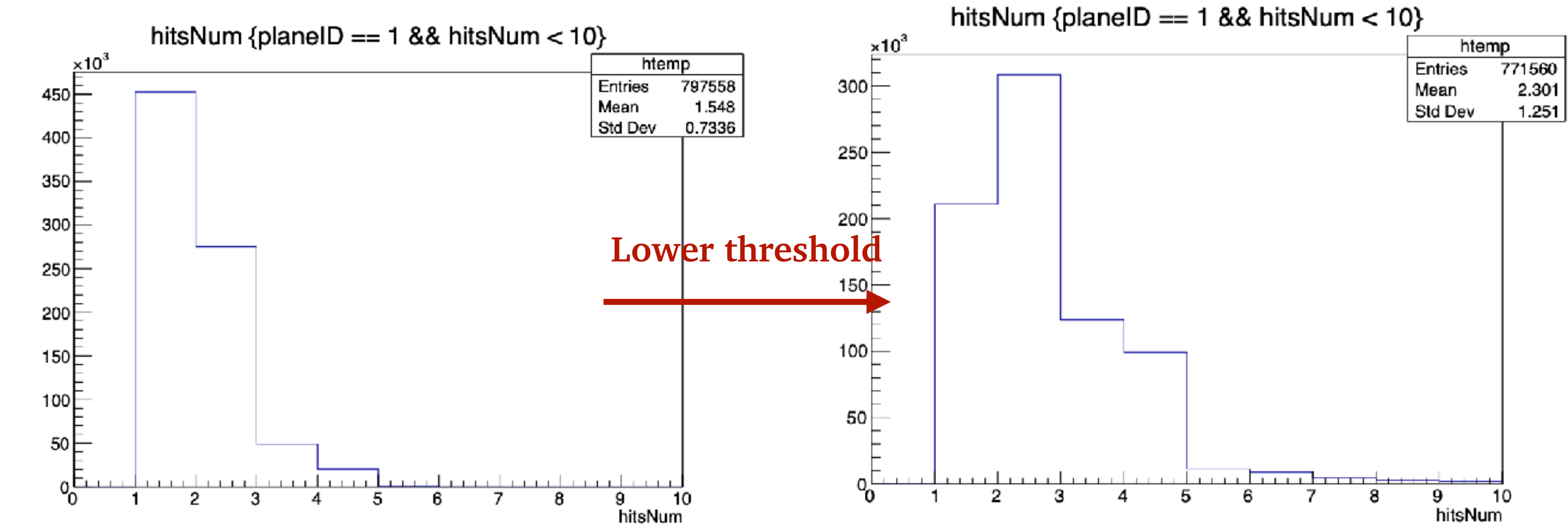
$$\chi^2 \text{ definition: } \chi^2(\alpha) = \sum_{i=1}^n \frac{f(x_i, \alpha) - e_i)^2}{\sigma_i^2}, \quad n = 5, \quad \text{sigmax} = \text{sigmay} = 25\mu\text{m}/\sqrt{12}$$



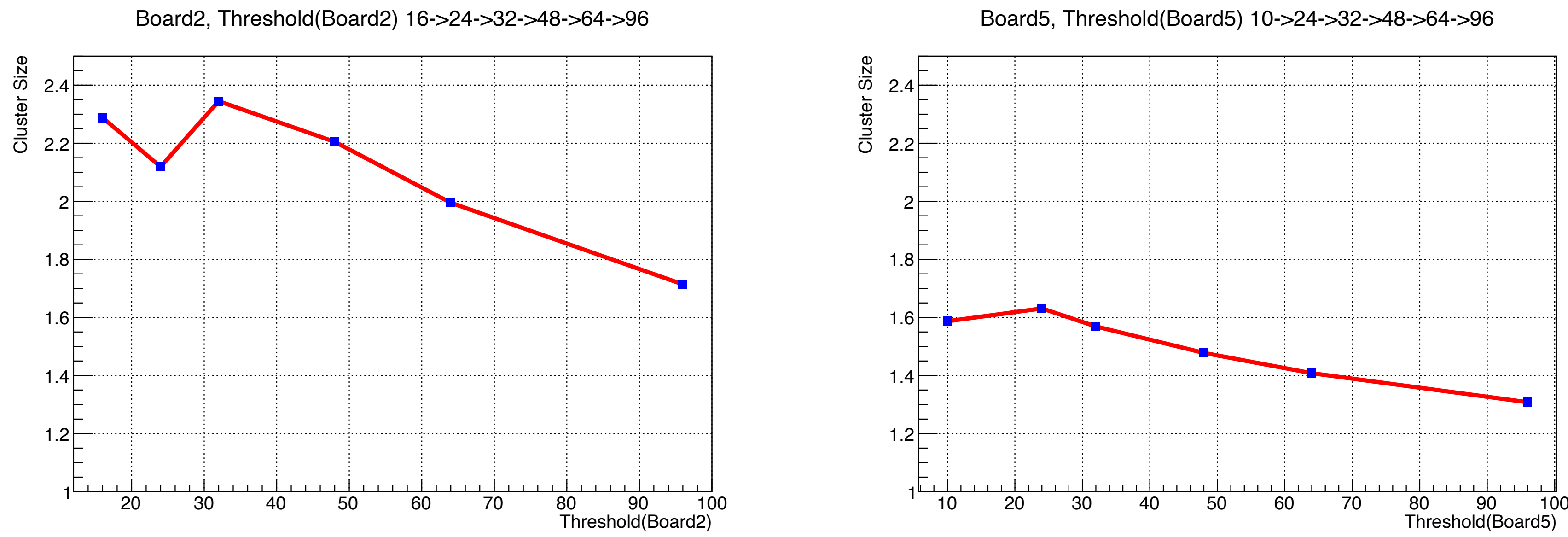
- The misalignment can be well corrected.
- The spatial resolution can reach $< 5\mu\text{m}$
- $\sigma_{\text{meas}}^2 = \sigma_{DUT}^2 + \sigma_{\text{tel}}^2$
- $\sigma_{DUT} \approx 0.91\sigma_{\text{meas}}$



Cluster size vs. chip threshold (4GeV)

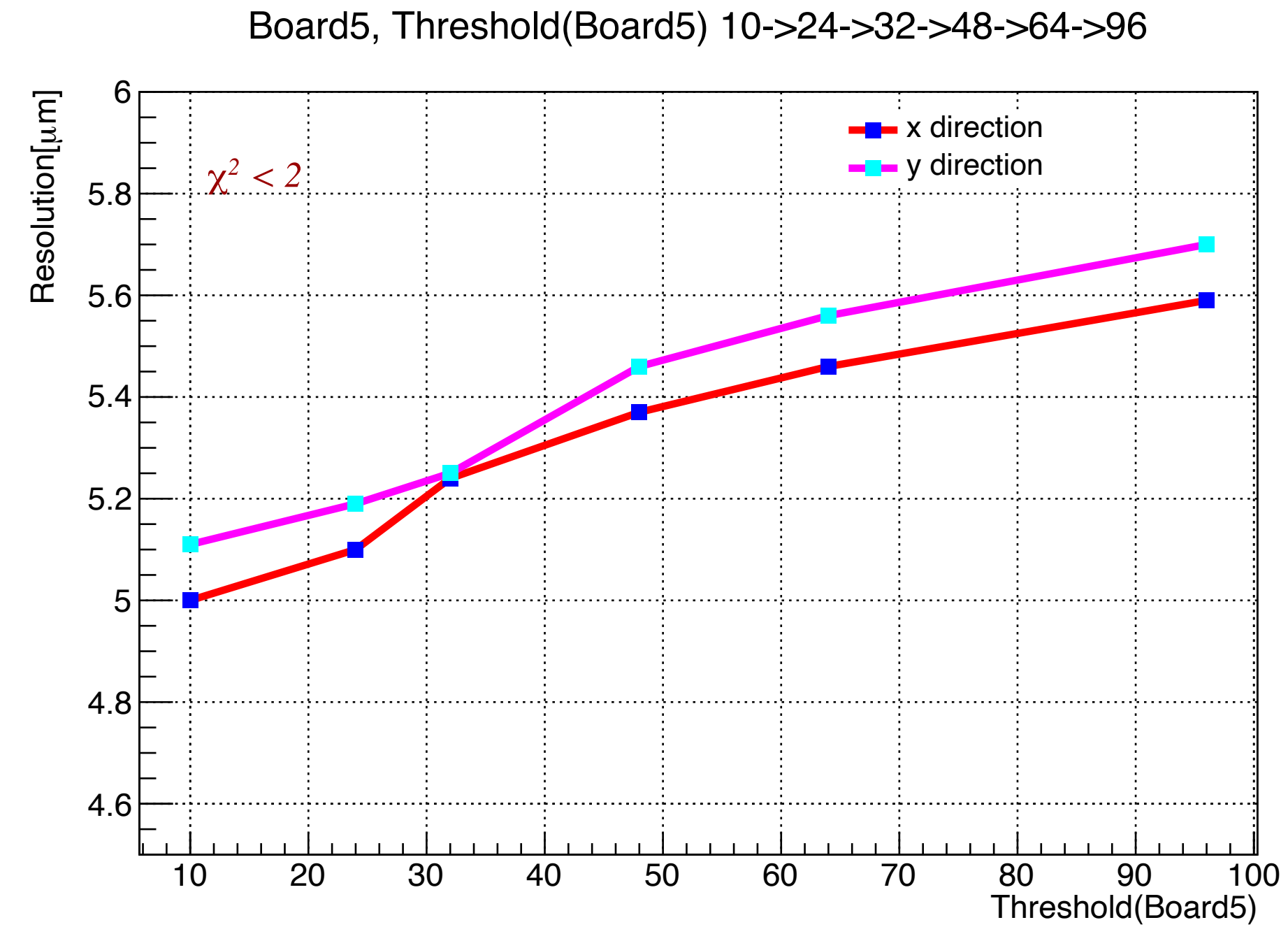
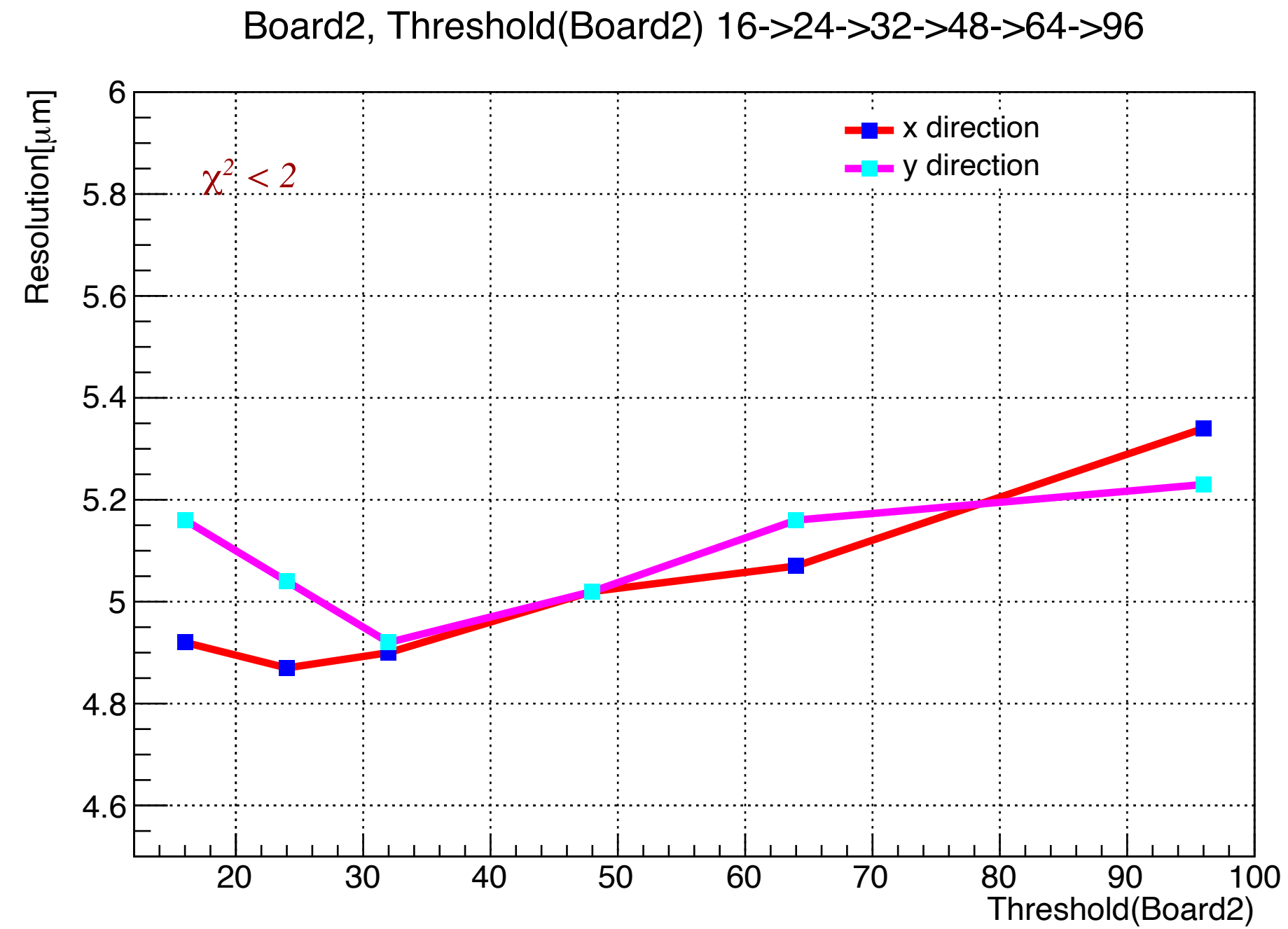


- If lowering the threshold, cluster size will be dominated by cluster with 2 hit



- Board2 with modified technology has a larger depletion layer than Board5 with standard technology
- In general, the higher the threshold, the smaller the cluster size

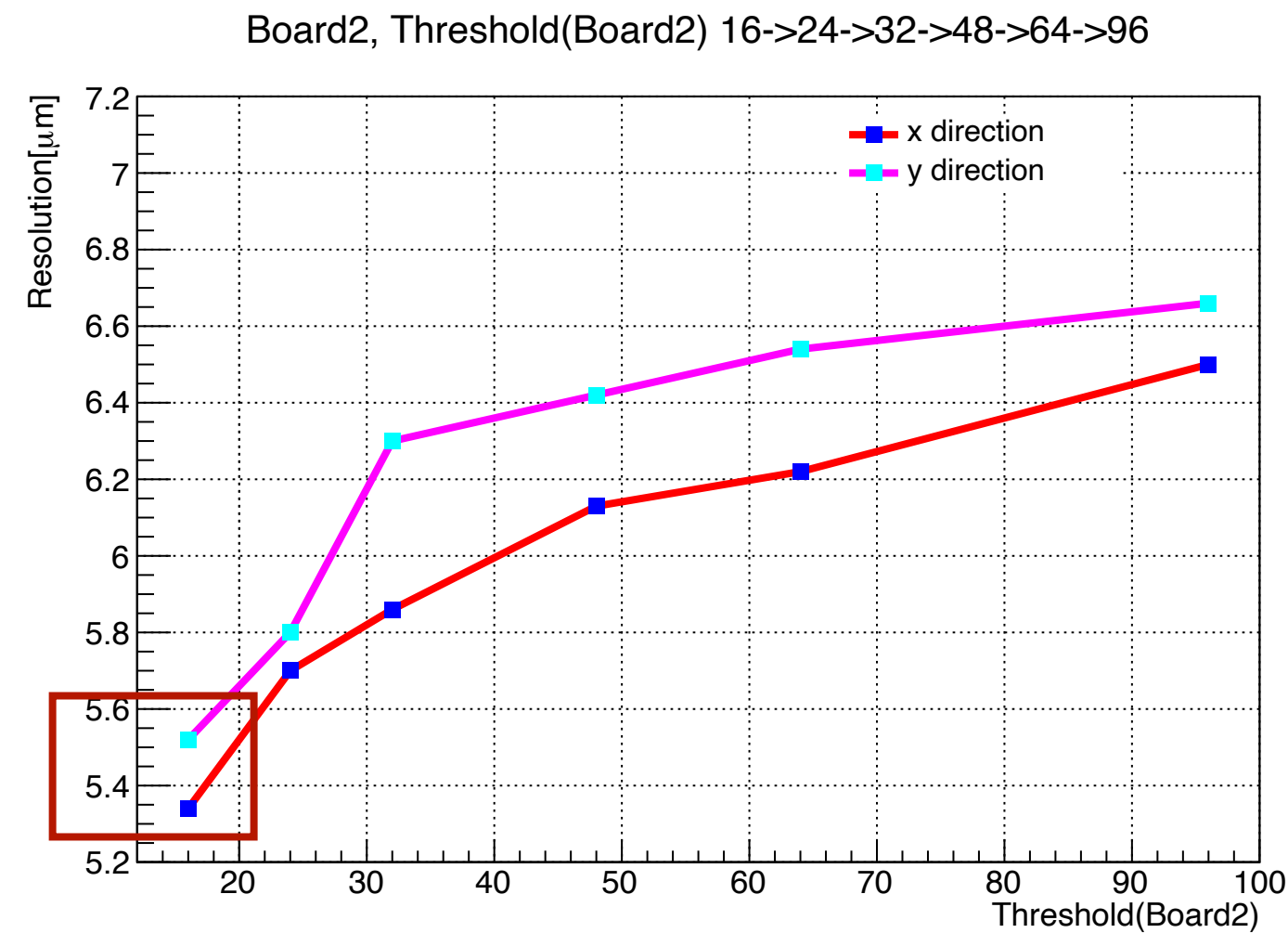
► Spatial resolution vs. chip threshold (4GeV)



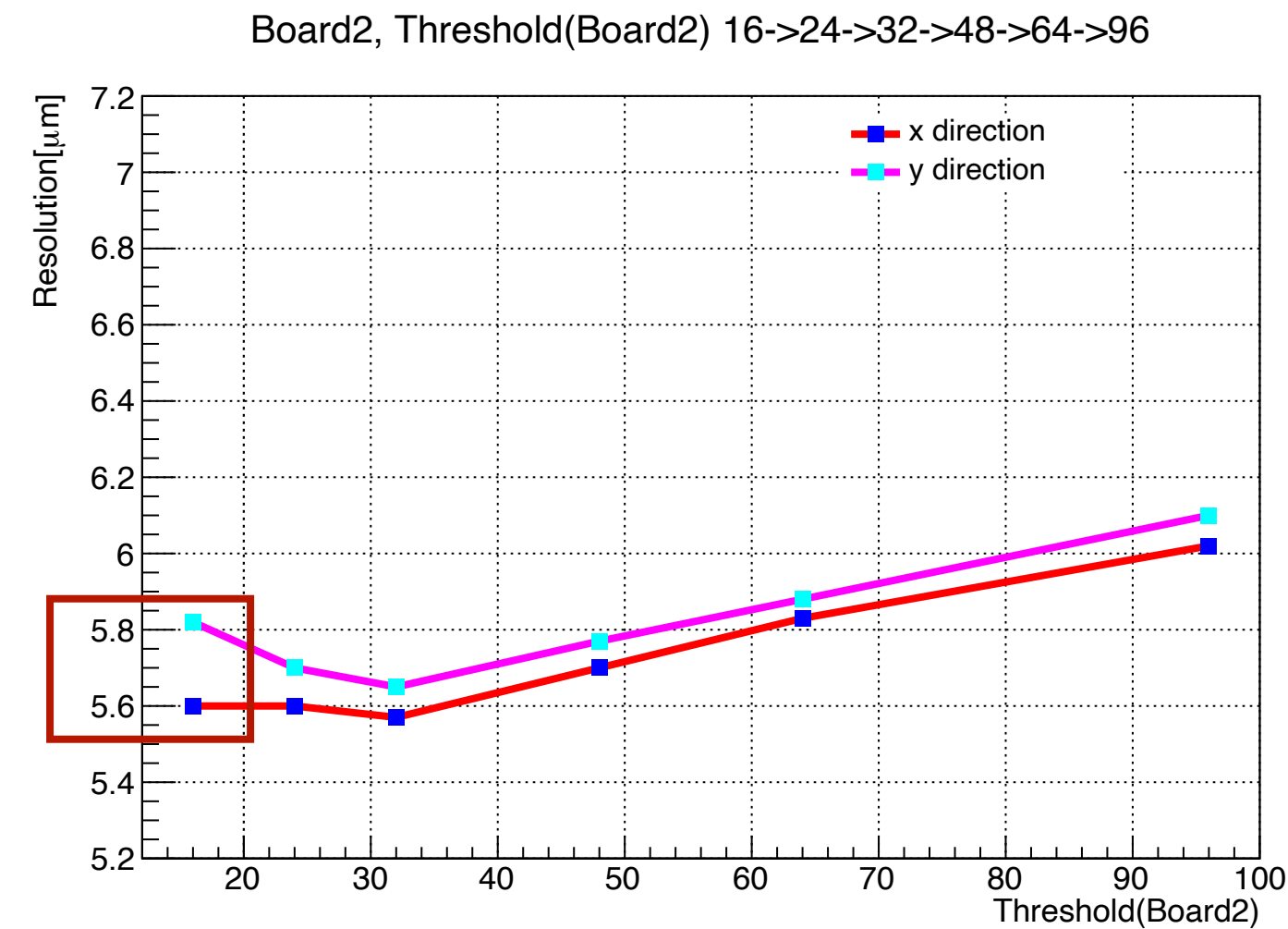
- Board2 with modified technology has a larger depletion layer than Board5 with standard technology
- In general, the higher the threshold, the worse the resolution

► Spatial resolution vs. chip threshold (4GeV) [Comparison of Clustersize = 1 and Clustersize >= 1]

Board2(modified) ClusterSize == 1

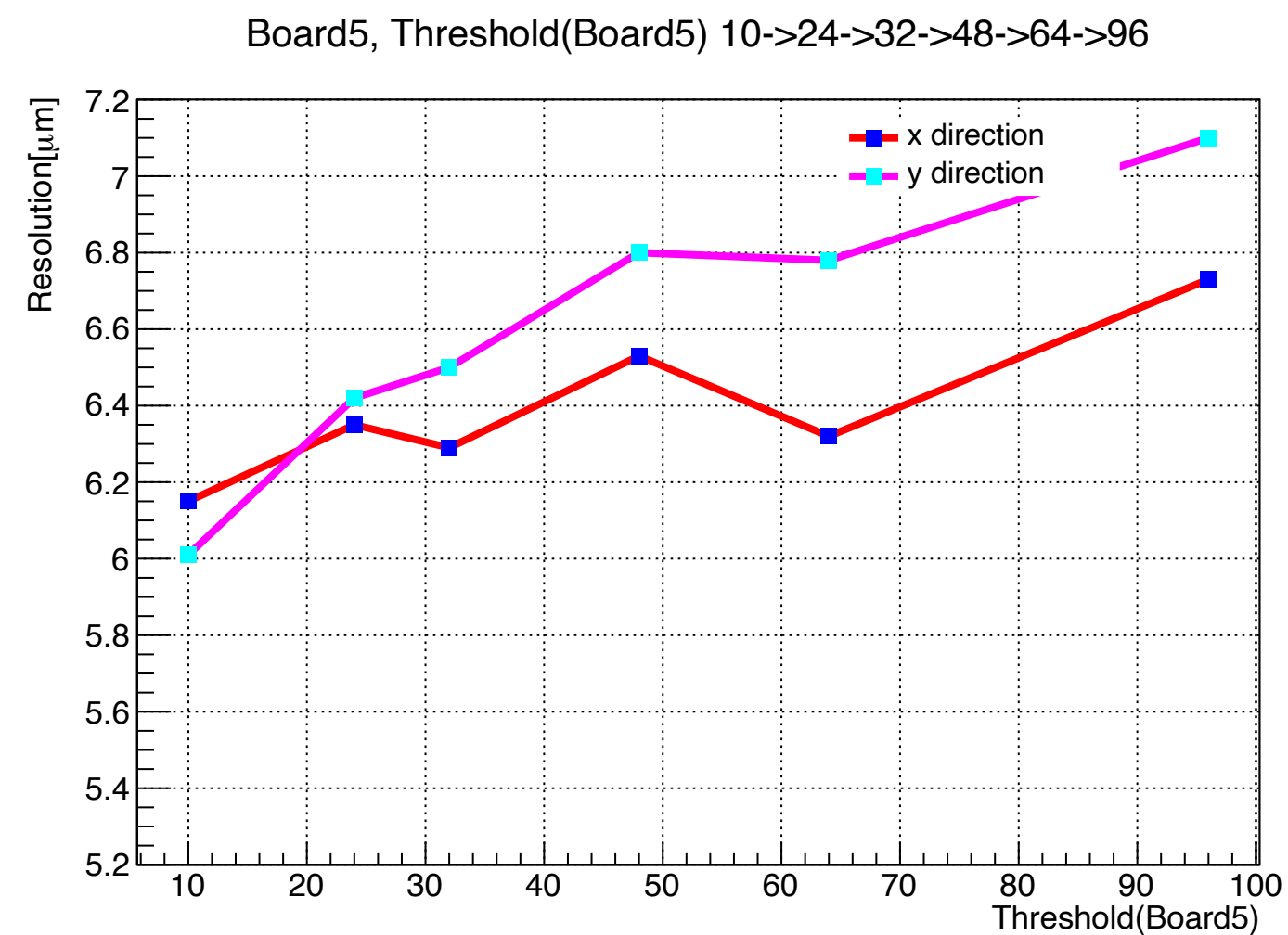


ClusterSize >= 1

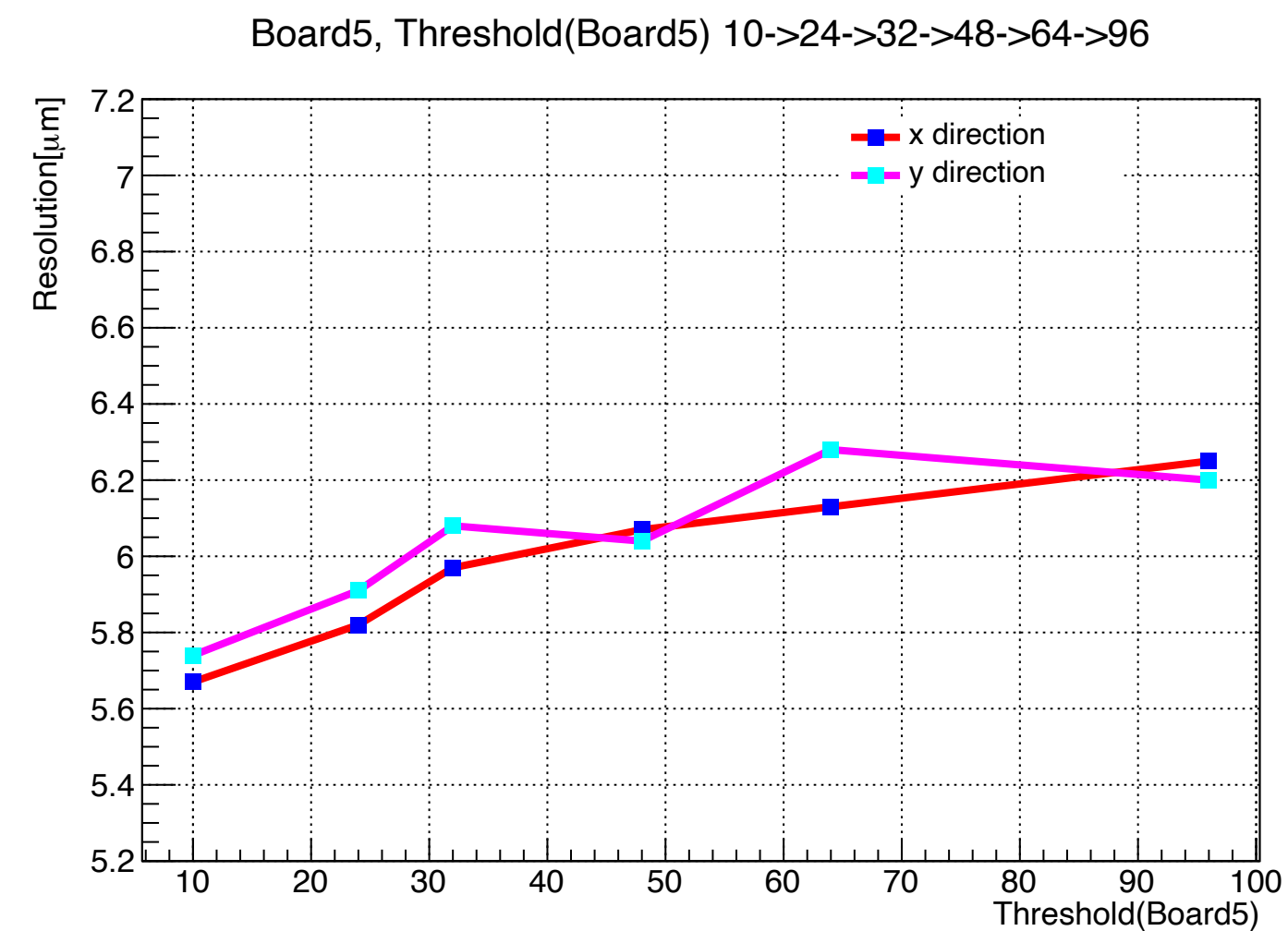


- Board2 with modified technology has a larger depletion layer than Board5 with standard technology
- ClusterSize = 1, only one hit in every cluster of every track (small statistics)
- ClusterSize >= 1, no cut on cluster size
- $\chi^2 < 8$
- Only when the modified chip2 threshold is equal to 16 (minimum threshold), the resolution of single hit is better than the resolution of multi-hit

Board5(standard) ClusterSize == 1



ClusterSize >= 1

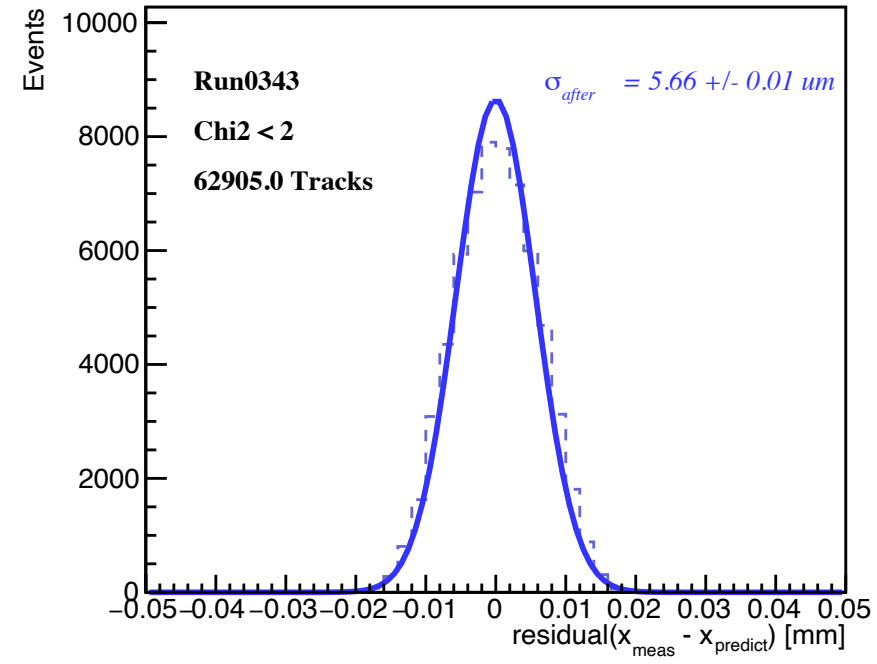


Summary

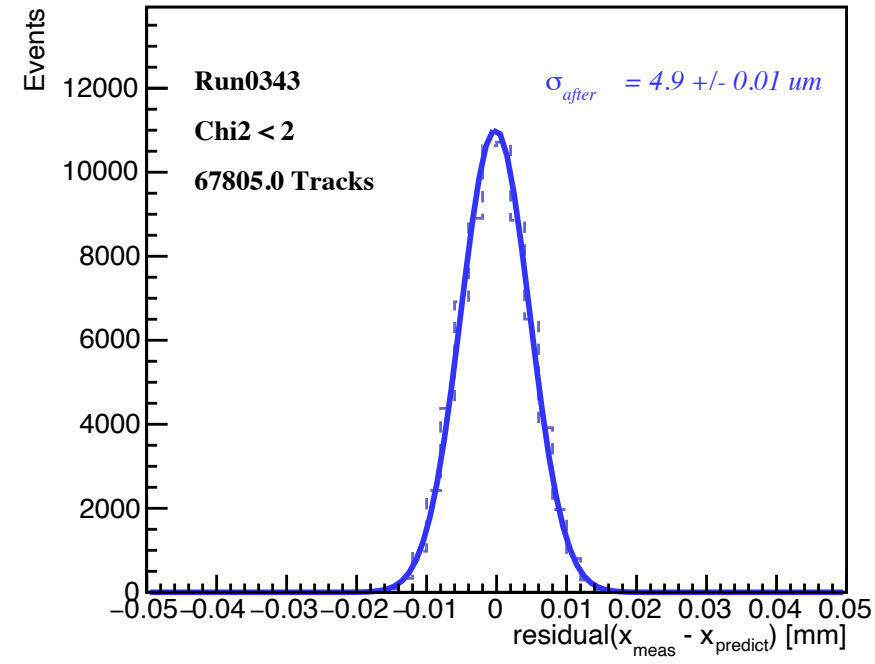
- ▶ The offline analysis framework can work well for CEPC vertex detector testbeam data
- ▶ The spatial resolution can $< 5\mu m$, satisfying MOST2 project index
- ▶ Next to do:
 - analyse more test beam data (different beam energy, the resolution of different region of chip...)
 - consider the multi-scattering effects using Kalman fitter

Backup

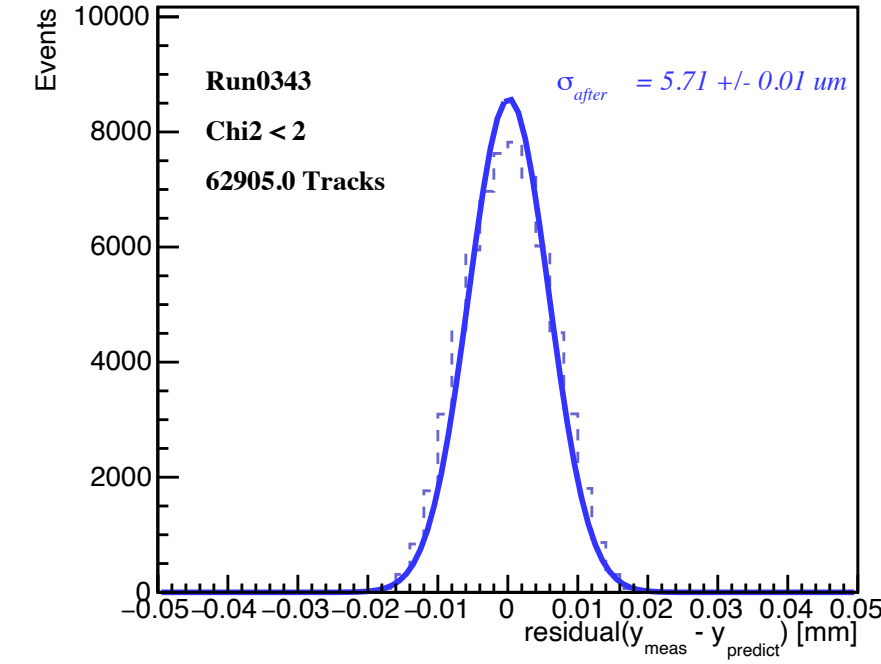
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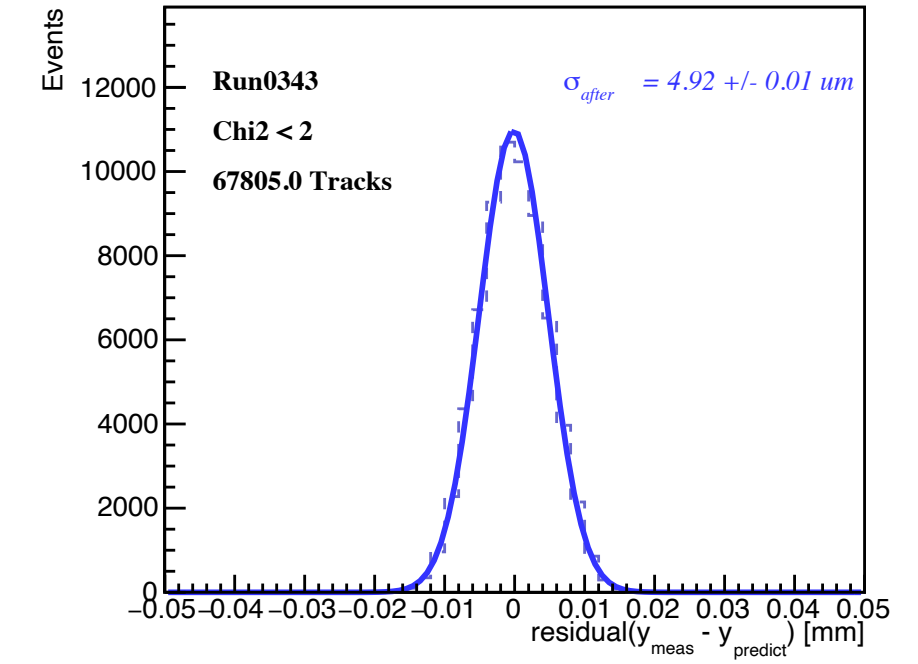
xdirection, ChipID = 1



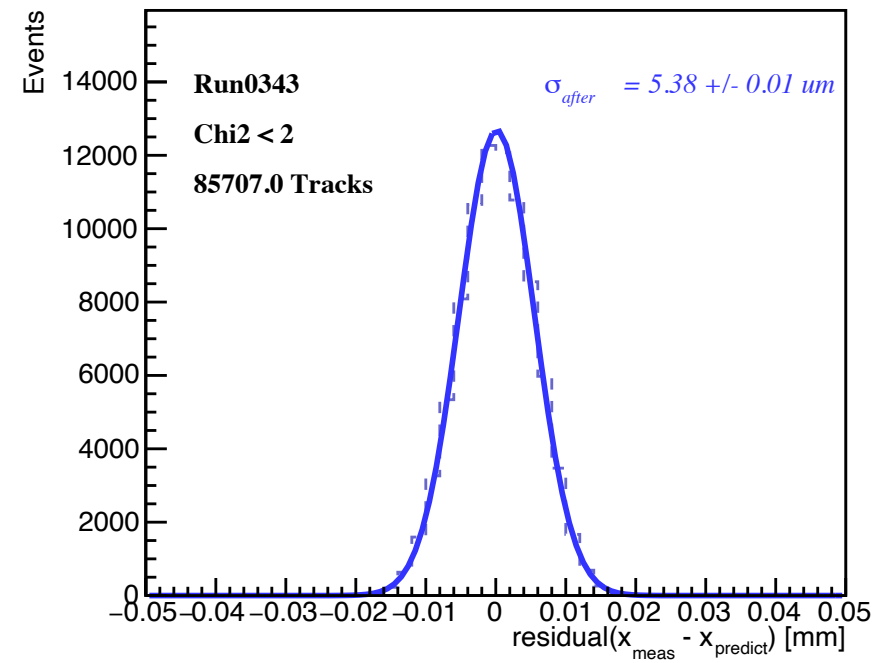
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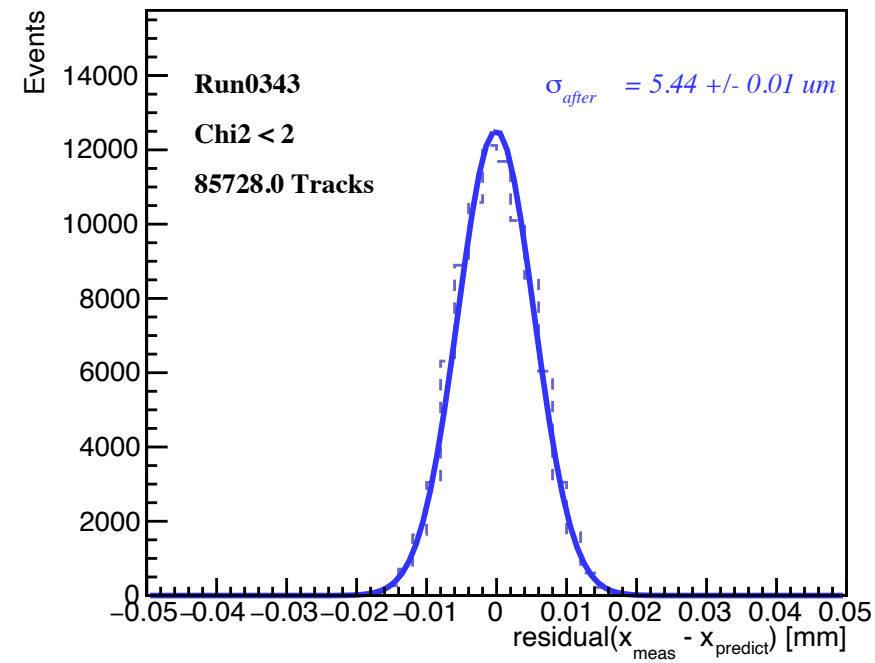
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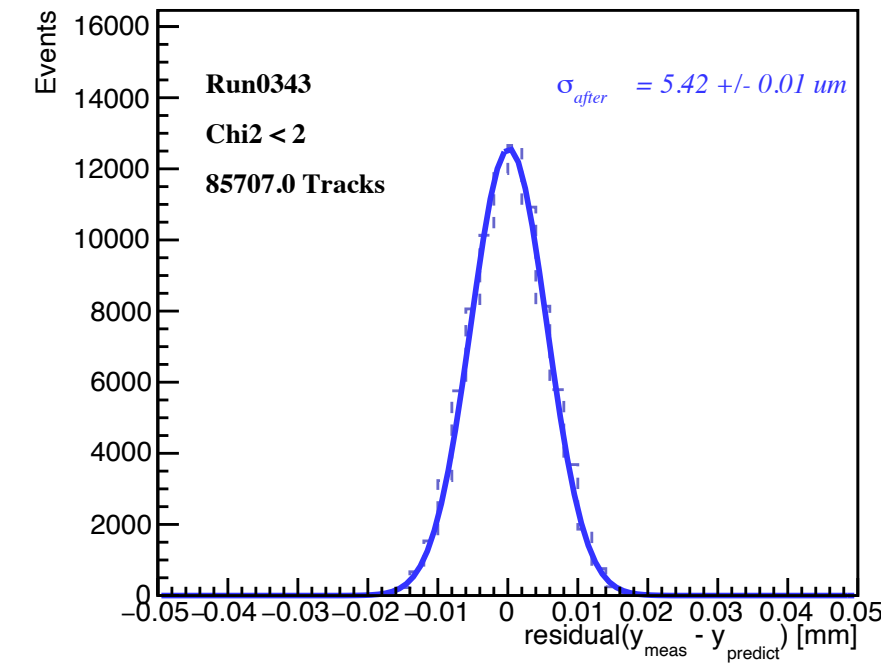
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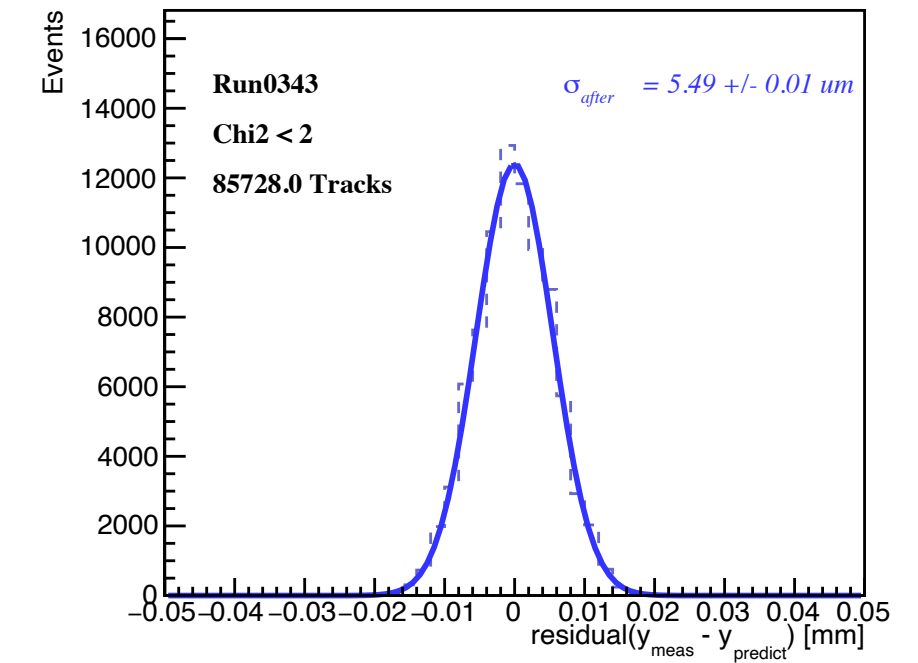
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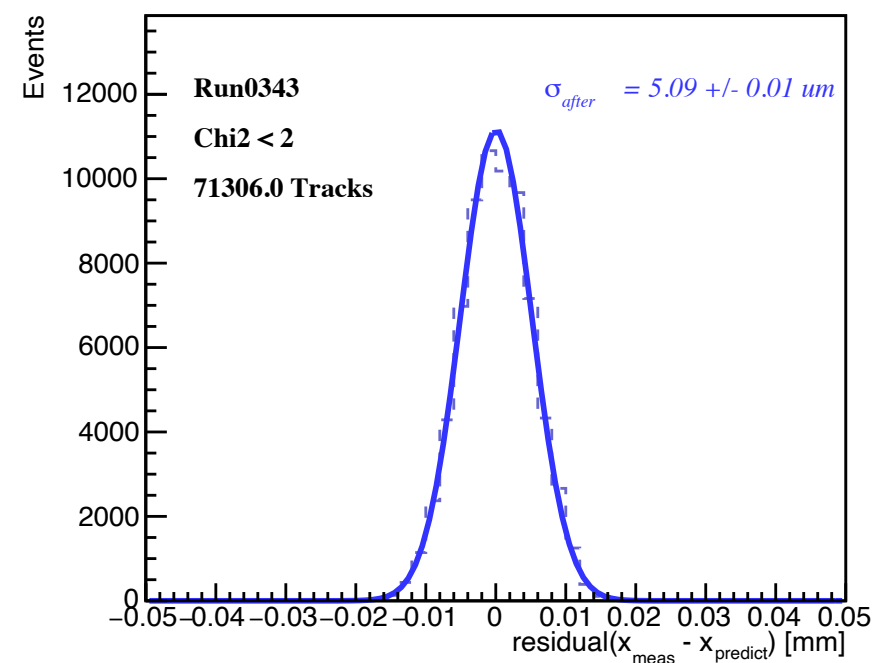
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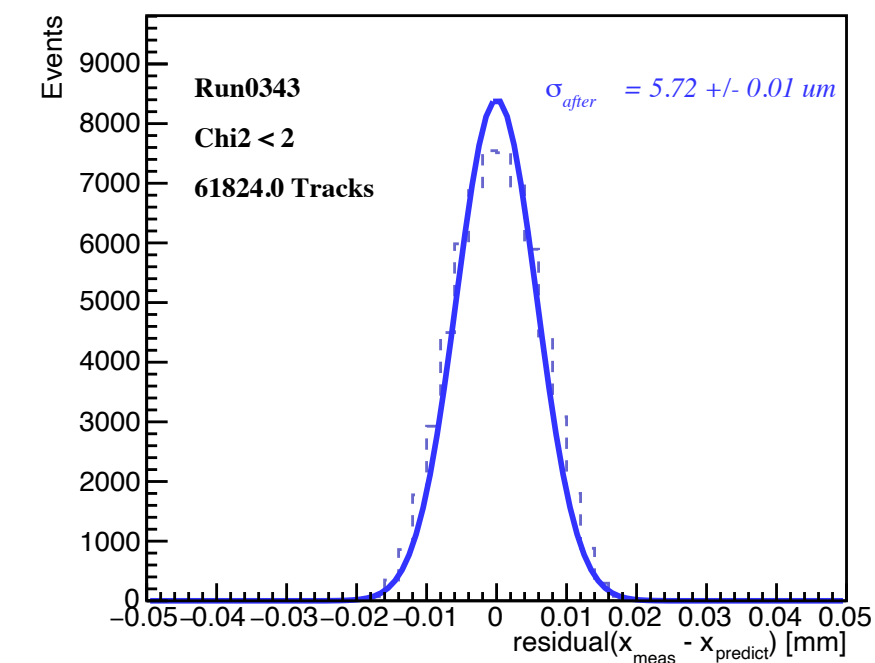
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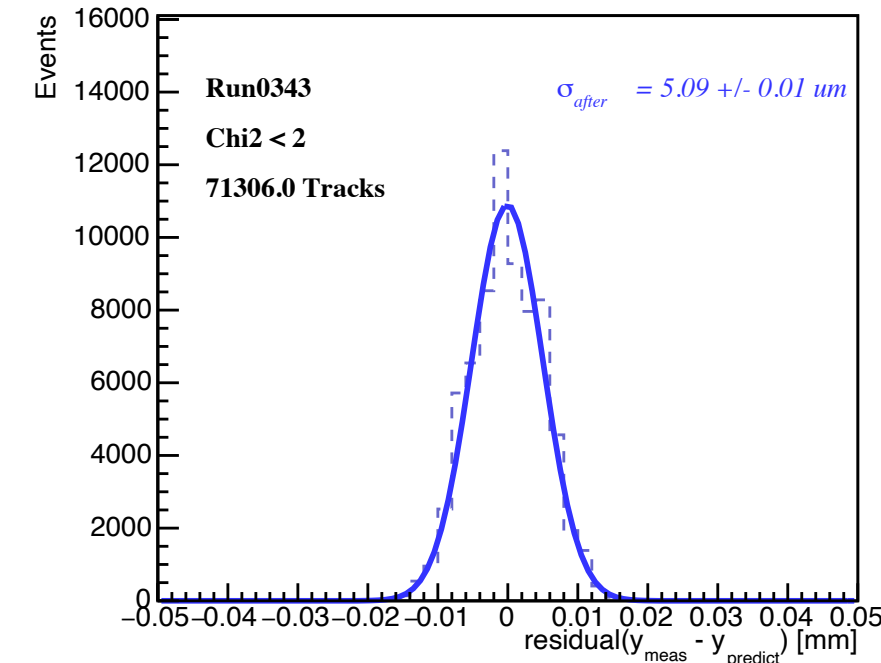
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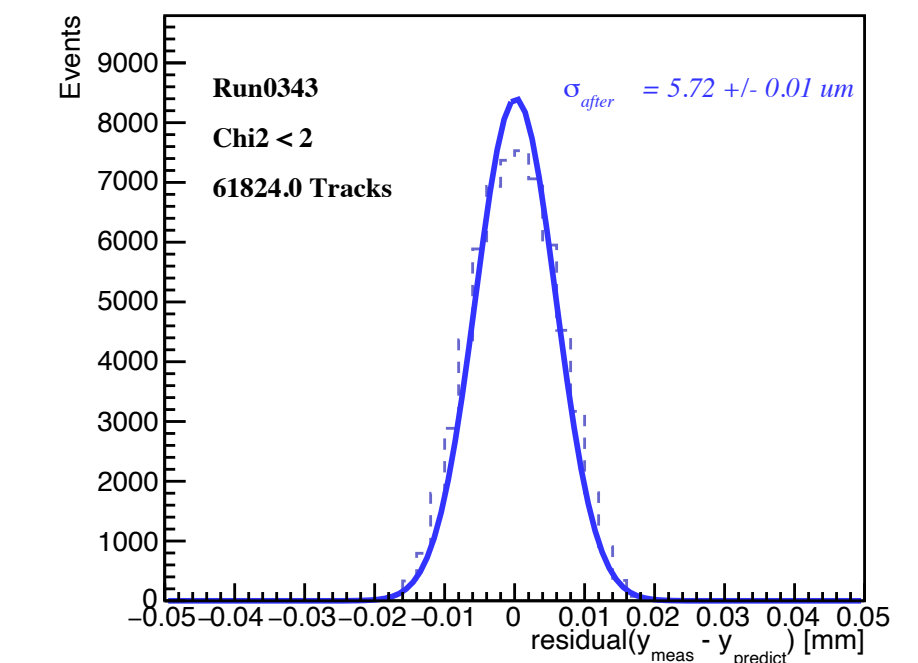
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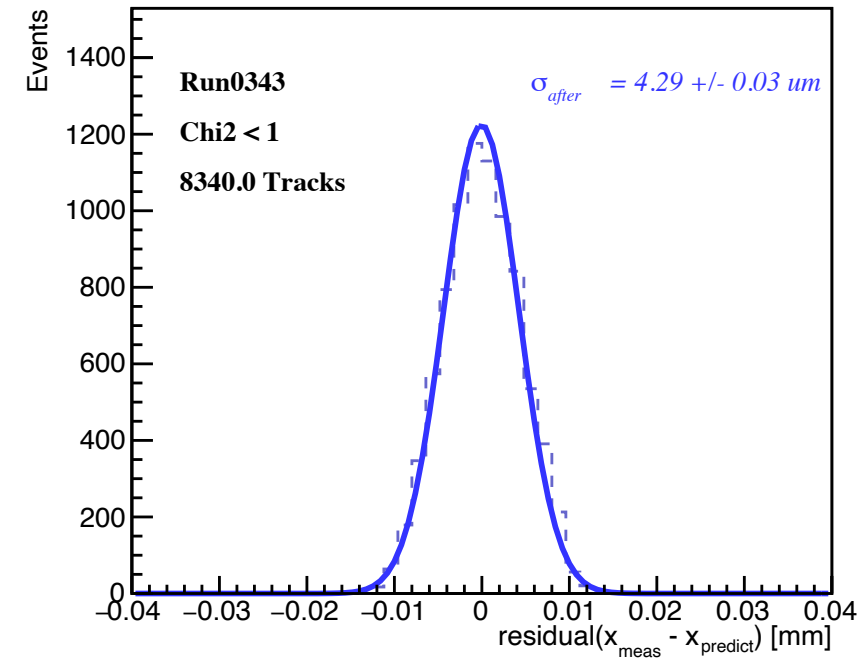
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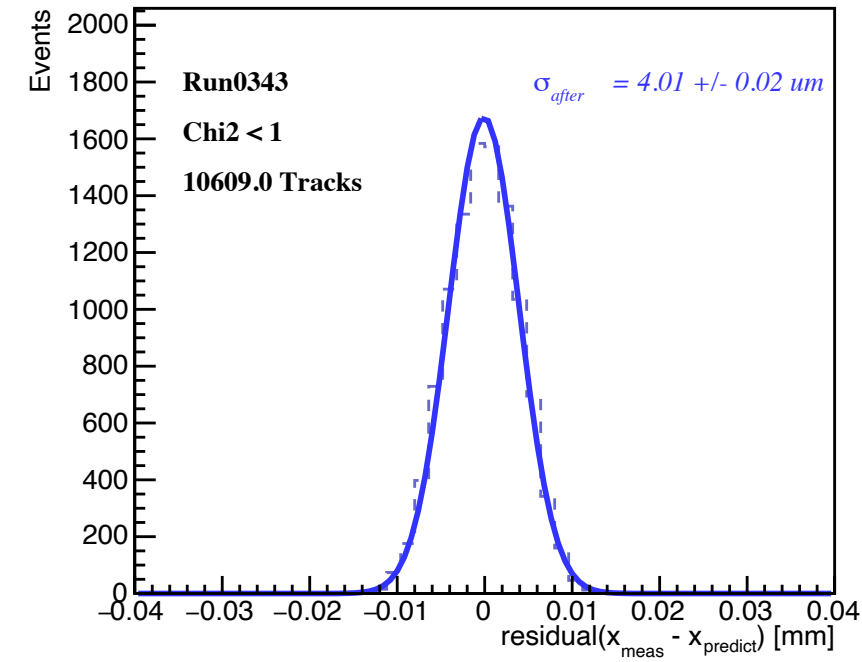
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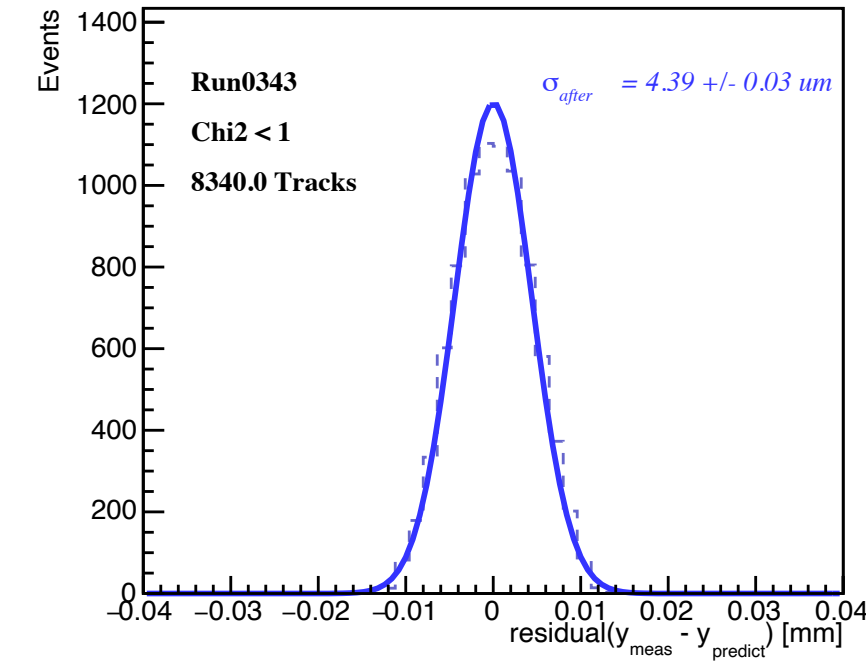
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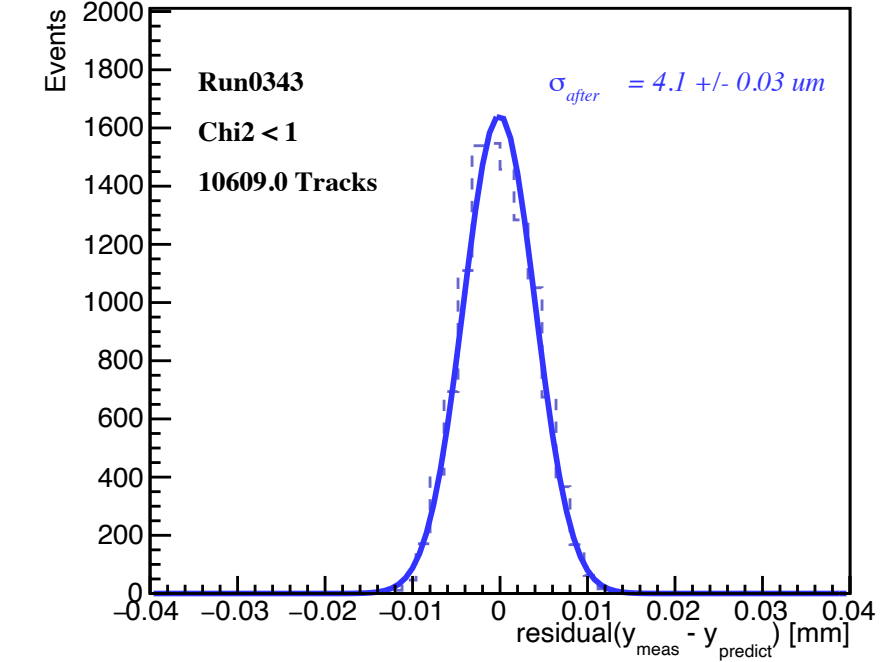
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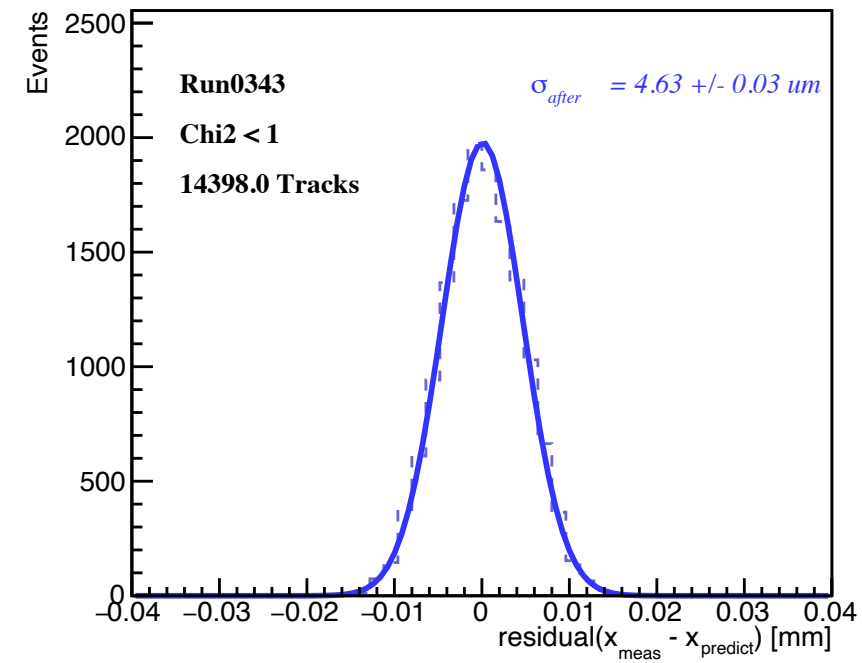
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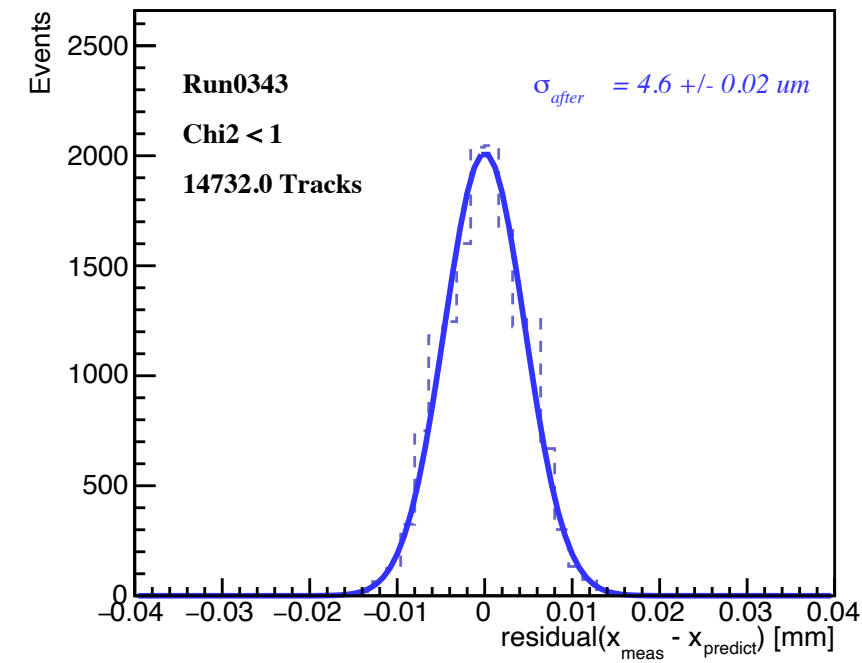
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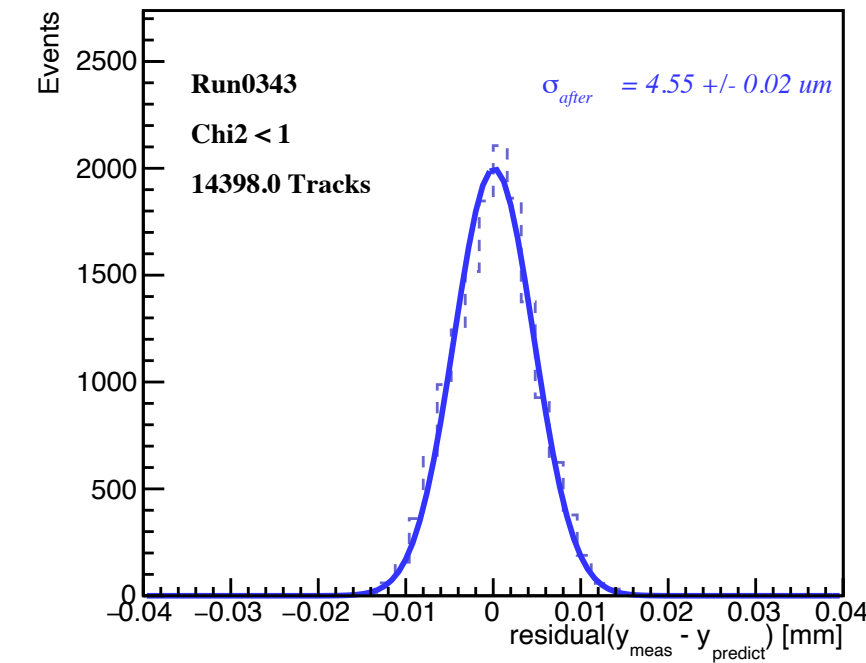
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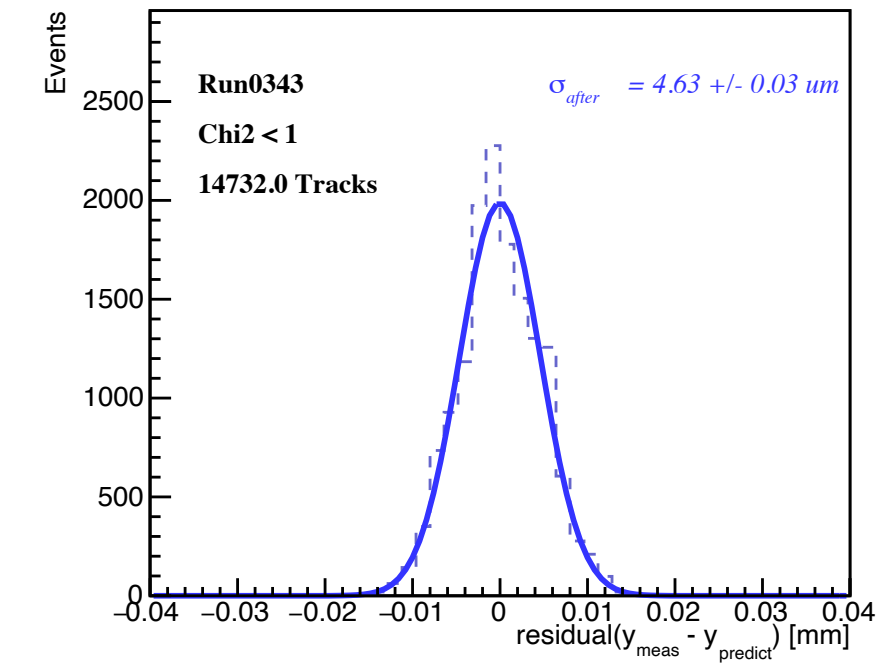
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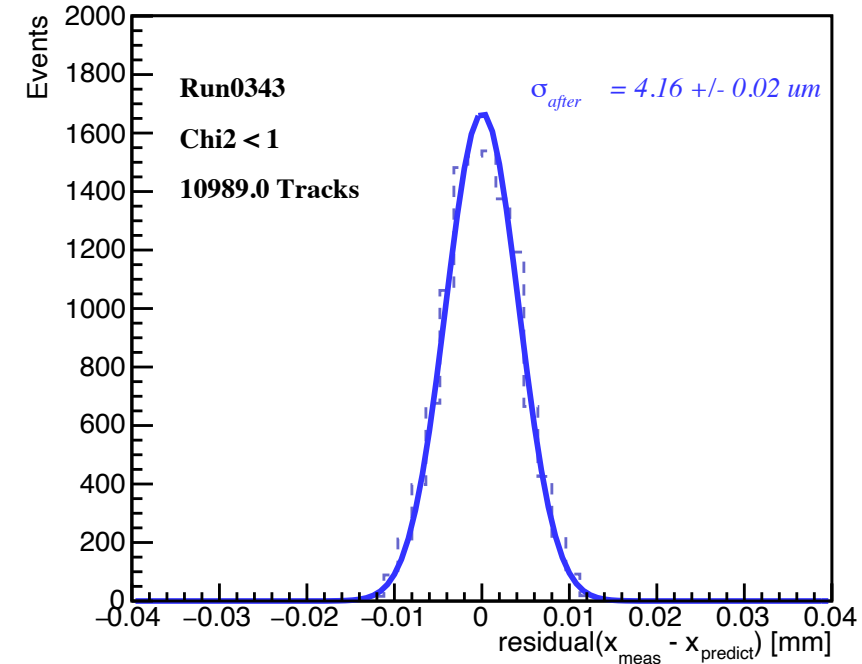
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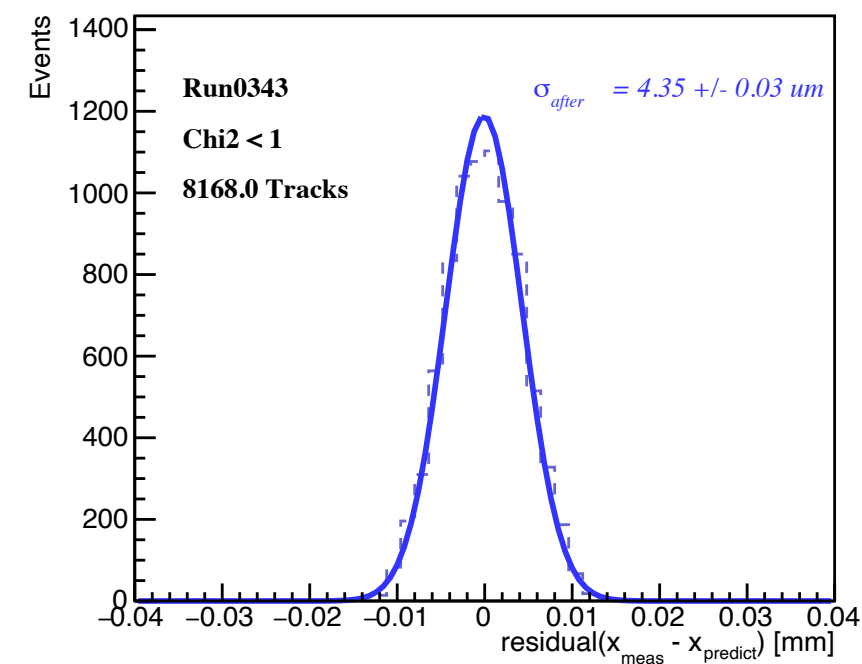
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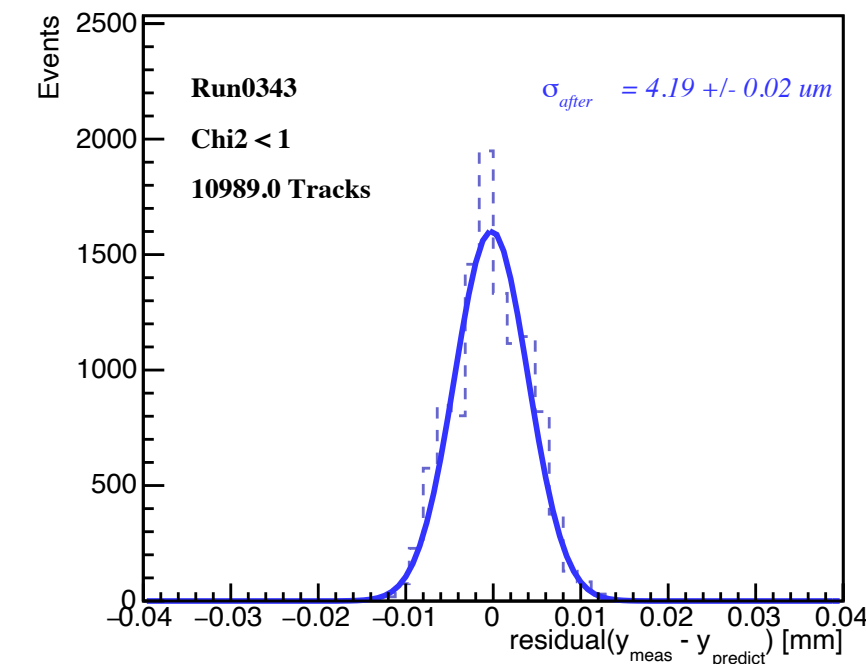
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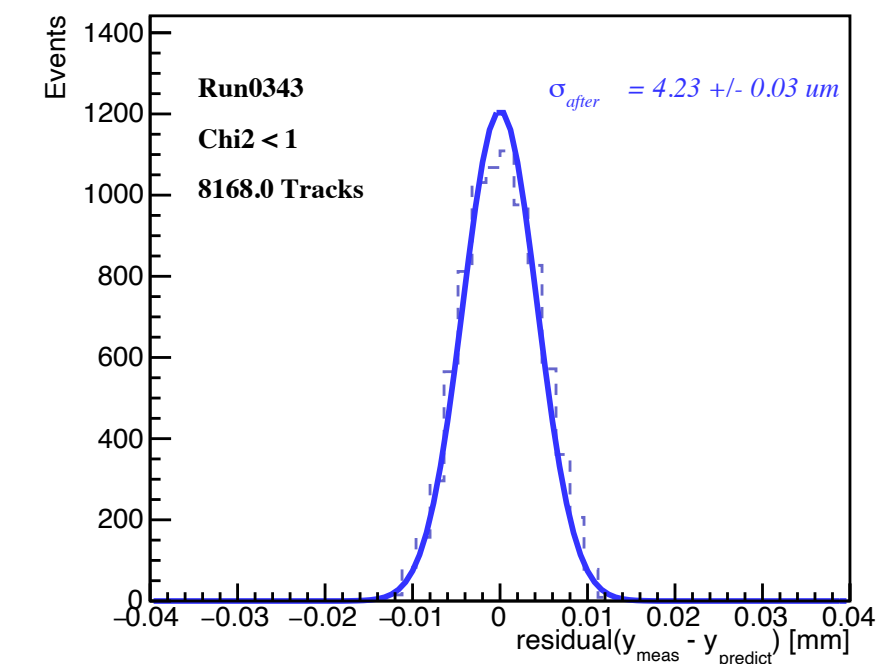
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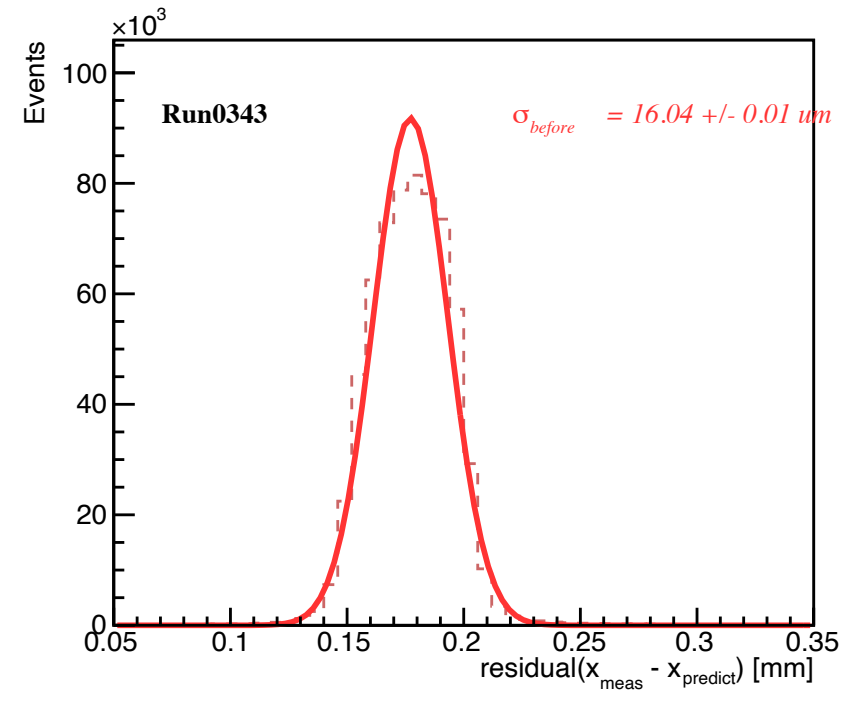
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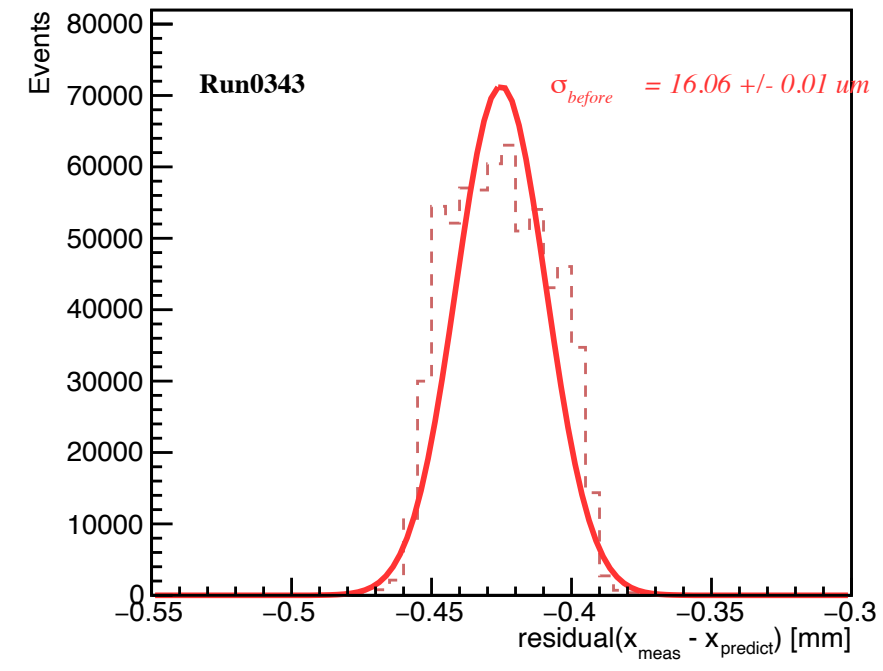
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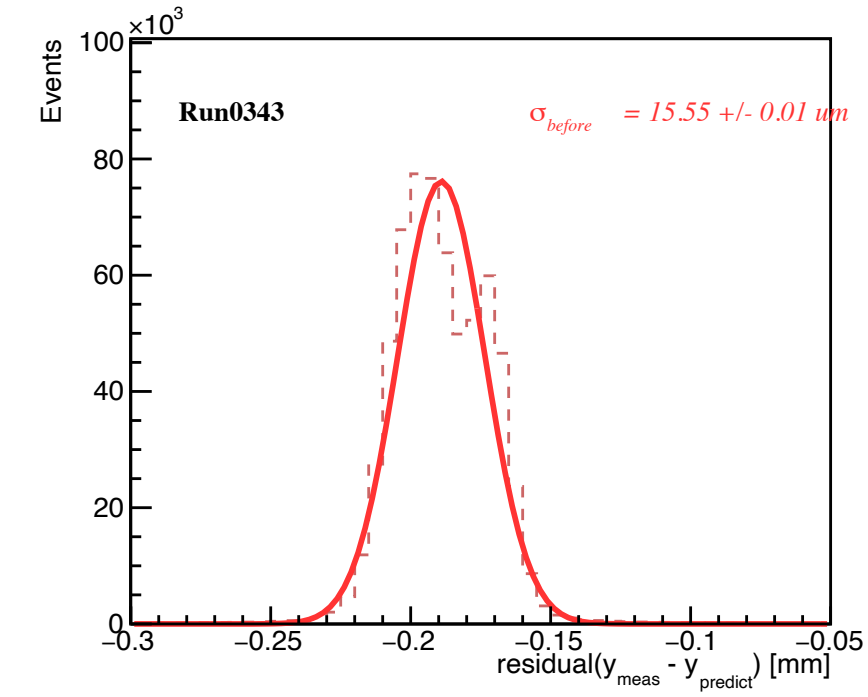
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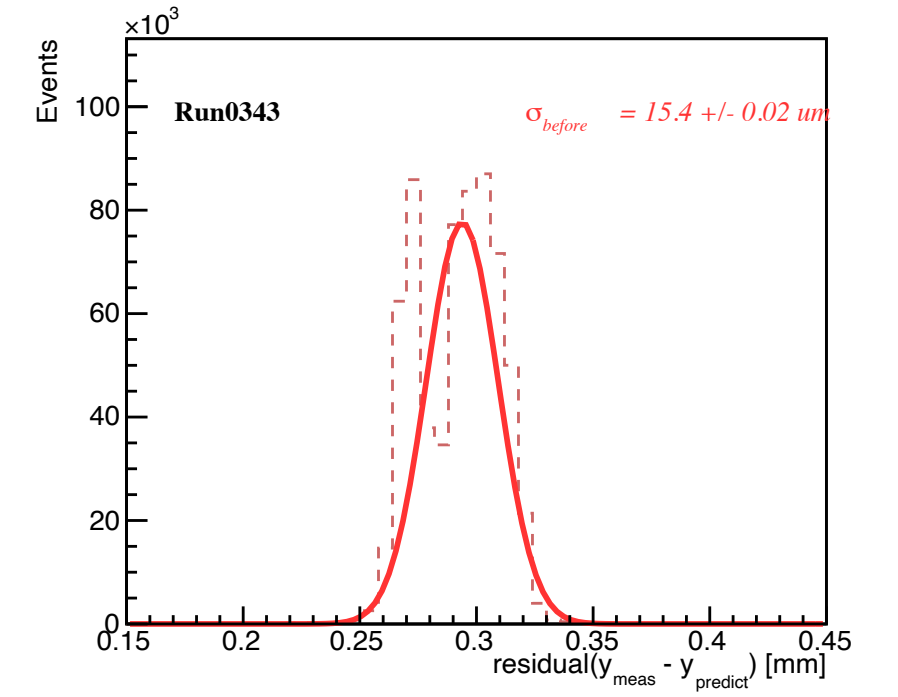
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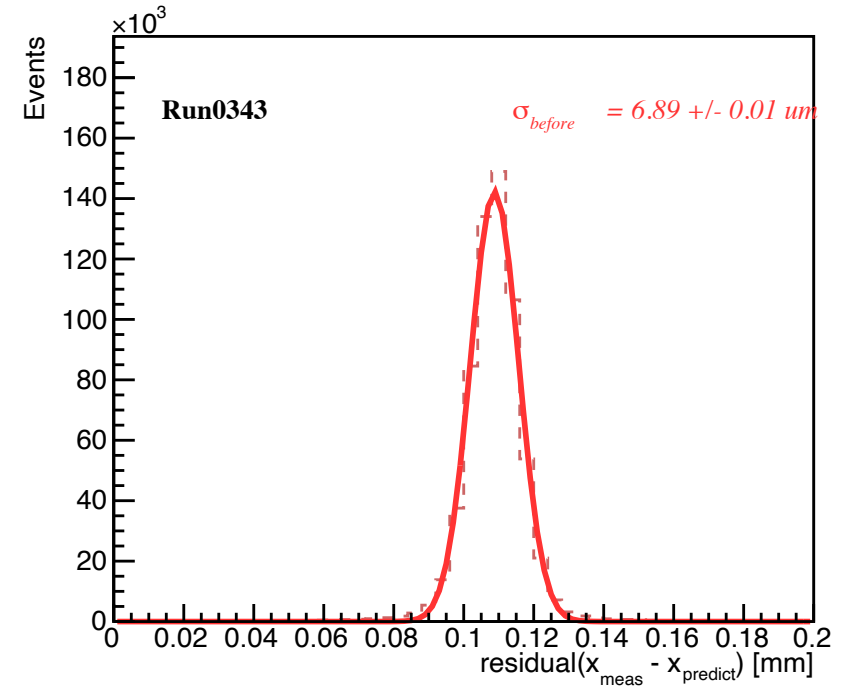
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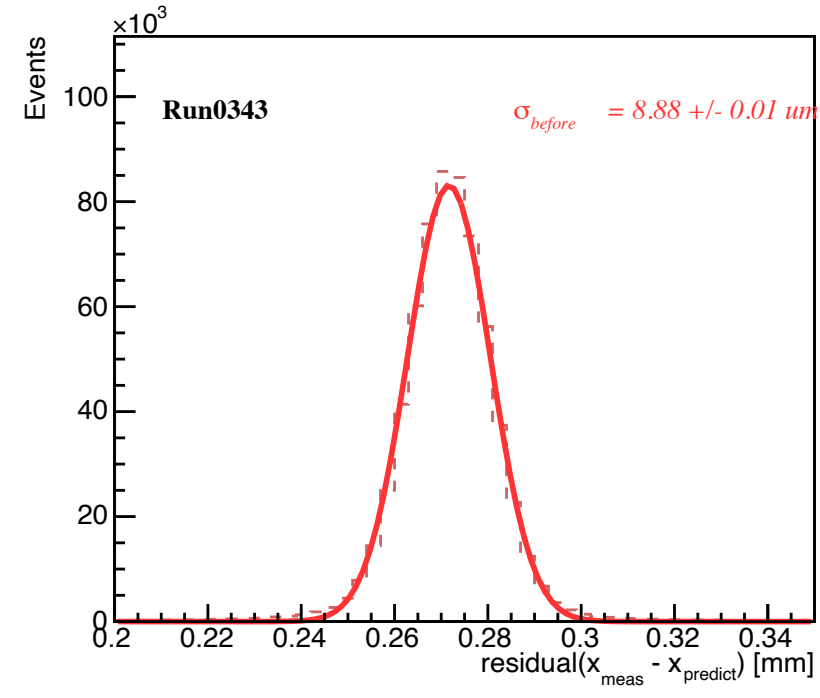
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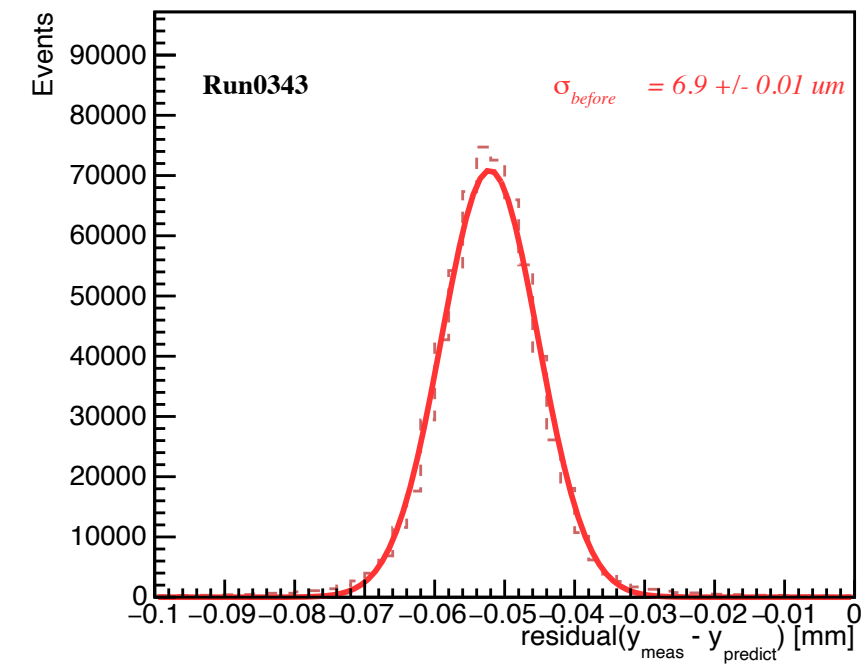
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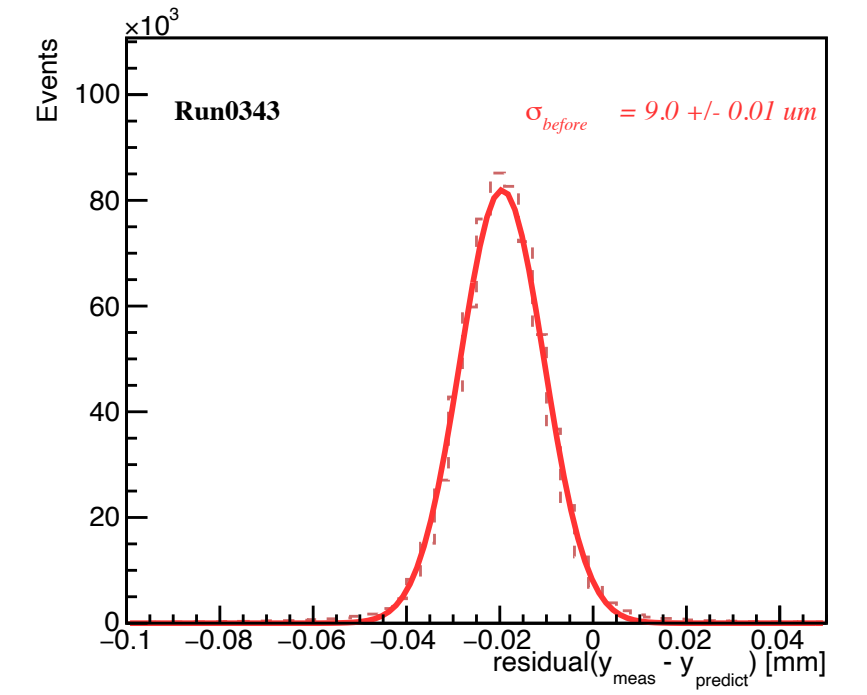
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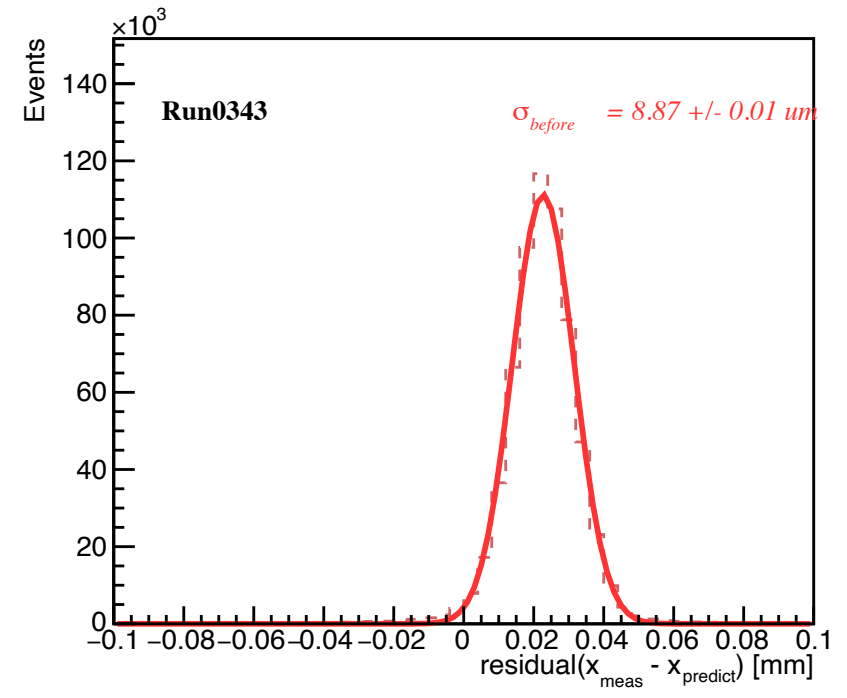
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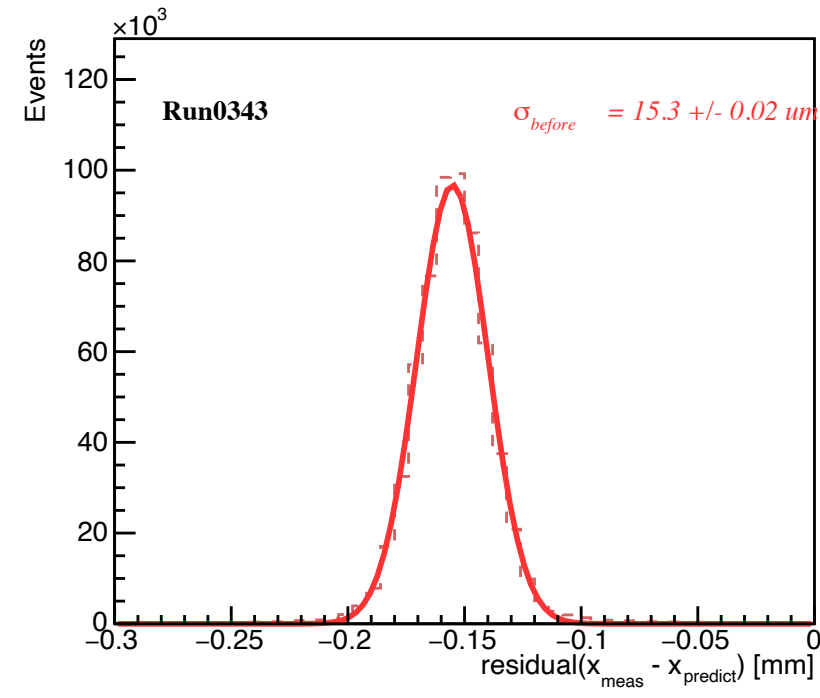
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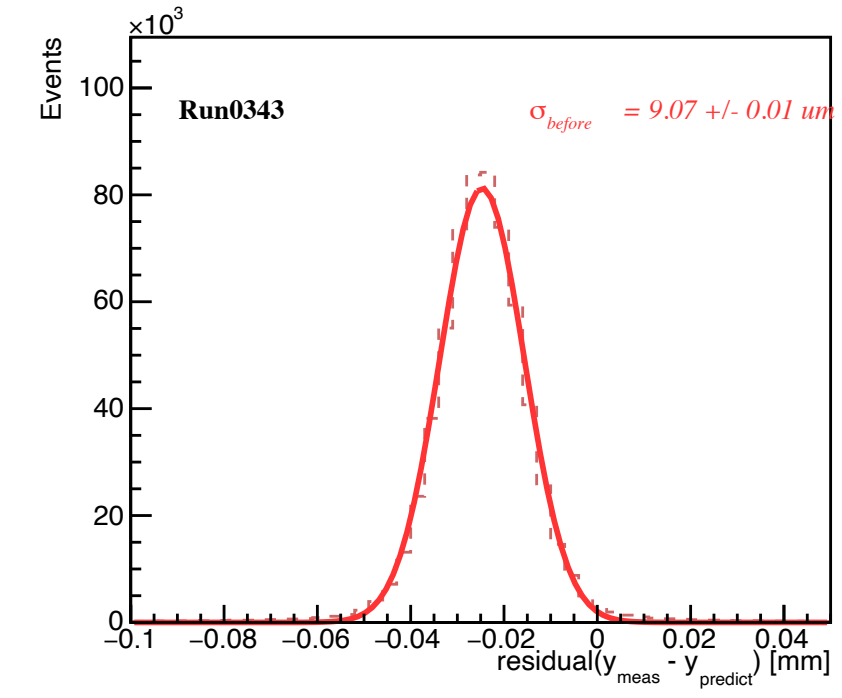
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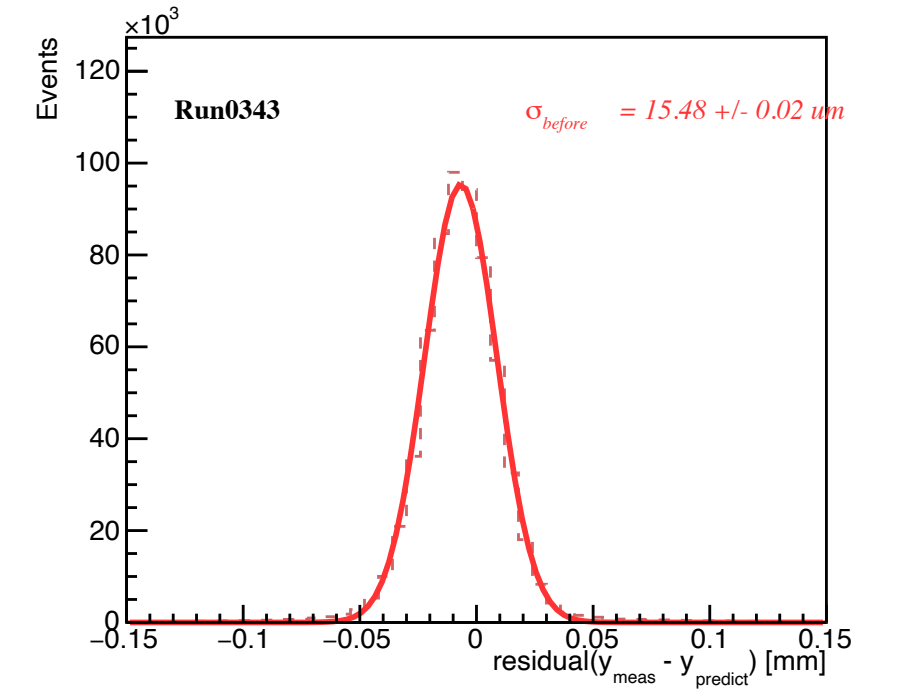
xdirection, ChipID = 5



ydirection, ChipID = 4



ydirection, ChipID = 5



The first step in the characterization of the telescope as a tracking device was the measurement of the intrinsic resolution of the reference planes and the ultimate spatial resolution achievable combining all the hits into a track. The single plane resolution (σ_{DUT}) can be obtained from the measured residual width (σ_{meas}) and the telescope resolution (σ_{tel}) using Eq. (1)

$$\sigma_{\text{meas}}^2 = \sigma_{\text{DUT}}^2 + \sigma_{\text{tel}}^2 \quad (1)$$

The telescope resolution can be determined assuming that the reference planes all have the same intrinsic resolution using Eq. (2)

$$\sigma_{\text{tel}}^2 = k\sigma_{\text{plane}}^2 \quad (2a)$$

and

$$k = \frac{\sum_i^N z_i^2}{N \sum_i^N z_i^2 - (\sum_i^N z_i)^2} \quad (2b)$$

The formula for the geometrical scaling factor k defined in (2b) is based on the assumption that the DUT is positioned at $z=0$ and it reduces to $1/N$ if the reference planes are is symmetrically distributed around the DUT and the beam and telescope axes are parallel.

Efficiency

Run0323:

B2= W9R5 iTHR 64 ; B1 W2R3 iTHR 16 ; B3 W2R11 iTHR 16 ; B4 W9R6 iTHR32 ; B5 W2R29 iTHR10 ; B6 W2R12 iTHR16 ; Beam 4GeV

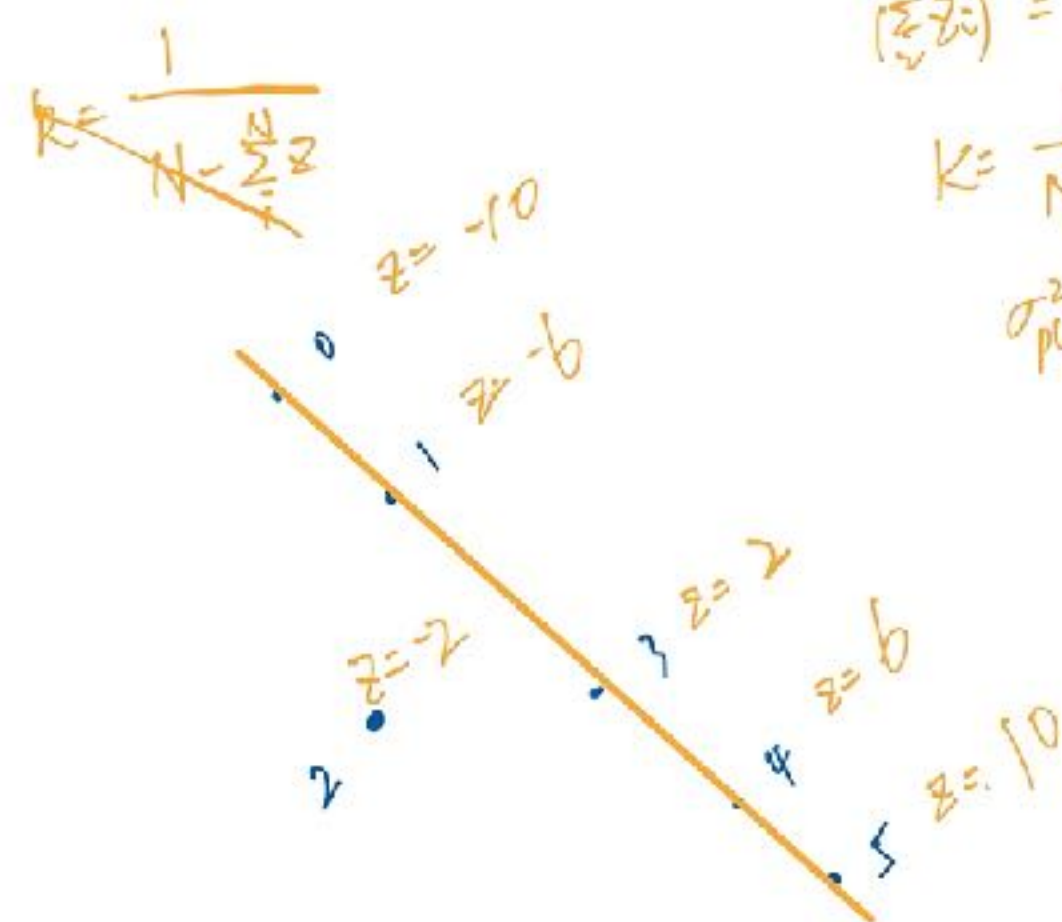
res k\Eff	1	2	3	4	5	6
1	0.98965	0.988425	0.986256	0.983358	0.990203	0.99068
2	0.996714	0.996881	0.997556	0.996325	0.997515	0.996402
3	0.997881	0.998177	0.998849	0.998072	0.998726	0.997648

Run0324:

B2= W9R5 iTHR 64 ; B1 W2R3 iTHR 16 ; B3 W2R11 iTHR 16 ; B4 W9R6 iTHR32 ; B5 W2R29 iTHR24 ; B6 W2R12 iTHR16 ; Beam 4GeV

res k\Eff	1	2	3	4	5	6
1	0.989897	0.988696	0.986532	0.984041	0.989403	0.990067
2	0.996957	0.996826	0.997578	0.996378	0.997366	0.996201
3	0.998074	0.998126	0.998833	0.997983	0.998651	0.997496

$$k = \frac{1}{N - \frac{(\sum_{i=1}^N z_i)^2}{\sum_{i=1}^N z_i^2}} = \frac{1}{N}$$



plane 10 = 0. $\sum_{i=1}^N z_i^2 = 6^2 + 2^2 + 2^2 + 6^2 + 10^2 = 180$

$$(\sum_{i=1}^N z_i)^2 = (-6 - 2 + 2 + 6 + 10)^2 = 100$$

$$k = \frac{1}{N - \frac{100}{180}} = \frac{1}{5 - 0.55} = \frac{1}{4.44}$$

$$\sigma_{plane}^2 = \frac{1}{1 + \frac{1}{4.44}} \sigma_{true}^2 = \frac{4.44}{5.44} \sigma_{true}^2 = 0.816 \sigma_{true}^2$$

$$\sigma = 0.903 \sigma_{true}$$

$$k = \frac{1}{5} \quad \sigma_{tot}^2 = \frac{\frac{1}{5}}{1 + \frac{1}{5}} = \frac{\frac{1}{5}}{\frac{6}{5}} = \frac{1}{5} \times \frac{5}{6} = \frac{1}{6} \quad \sigma_{tot}^2 = \frac{1}{6} \cdot \sigma_{true}^2 \quad \sigma_{tot} = \frac{1}{\sqrt{6}} \sigma_{true} = 0.408 \sigma_{true}$$

plane 10 = 1 $\sum_{i=1}^N z_i^2 = 10^2 + 2^2 + 2^2 + 6^2 + 10^2 = 244$

$$(\sum_{i=1}^N z_i)^2 = (10 - 2 + 2 + 6 + 10)^2 = 36$$

$$k = \frac{1}{5 - \frac{36}{244}} = \frac{1}{5 - 0.147} = \frac{1}{4.853}$$

$$\frac{1}{1 + \frac{1}{4.853}} = \frac{4.853}{5.853} = \sqrt{0.829} = 0.910$$

plane 10 = 2 $\sum_{i=1}^N z_i^2 = 10^2 + 6^2 + 2^2 + 6^2 + 10^2 = 276$

$$(\sum_{i=1}^N z_i)^2 = (-10 - 6 + 2 + 6 + 10)^2 = 4$$

$$k = \frac{1}{5 - \frac{4}{276}} = \frac{1}{5 - 0.0145} = \frac{1}{4.985}$$

$$\frac{1}{1 + \frac{1}{4.985}} = \frac{4.985}{5.985} = \sqrt{0.833} = 0.912688$$